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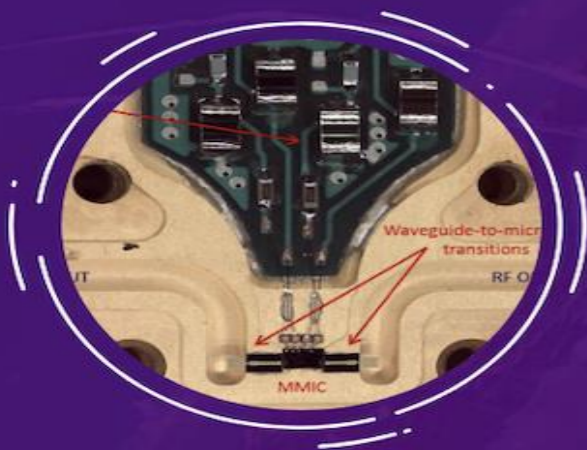
pHEMT Characterisation and SSEC Extraction from 4 K to 290 K

Long Jiang, William Mcgenn, Mark McCulloch, Elle Franks,
Amy Suddards, Danielle George and Gary A. Fuller

Advanced Radio Instrumentation
Group

University of Manchester

FACILITIES AND CAPABILITIES



Development of Microwave Components

Design of millimetre and sub-millimetre wavelength devices using MMIC technology.



S-parameters and Noise Measurements

Capability to measure S-parameters up to 330GHz and noise up to 110GHz



Integrated circuits and packaged devices

Measurements of MMICs and transistors to improve models and design

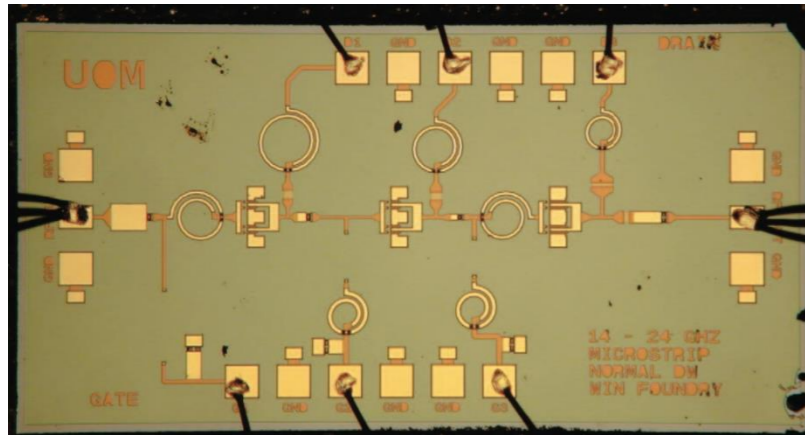


Cryogenic facilities

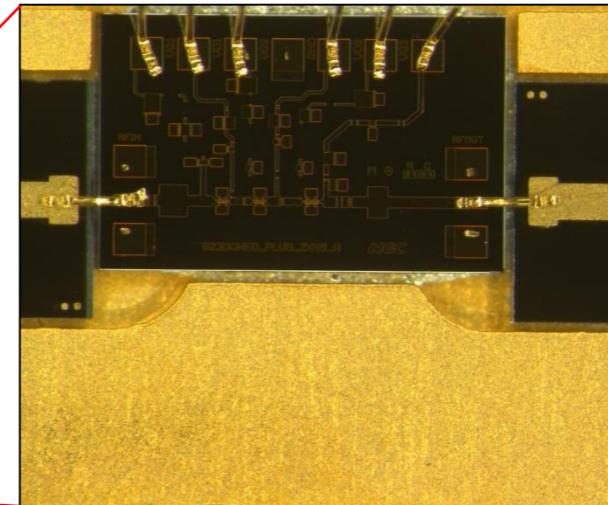
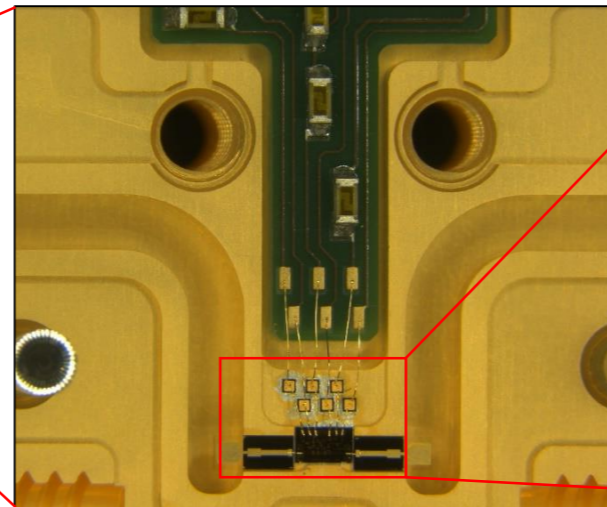
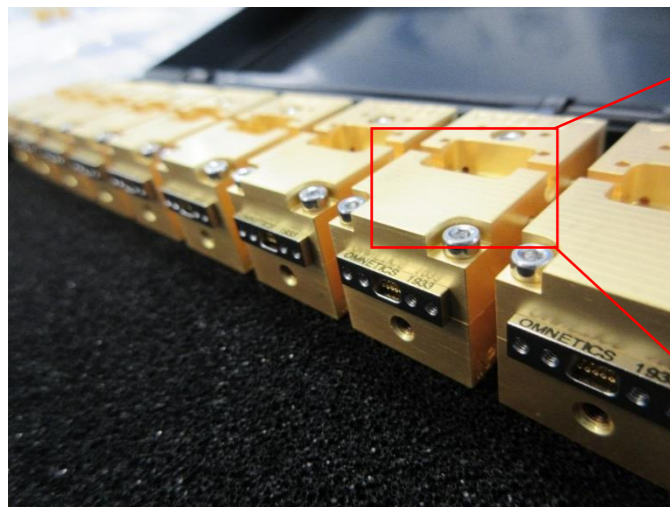
On-wafer cryogenic measurements at 4K and RF cryostat to measure down to 300mK

Focus on design and development of LNAs and front-end receiver instrumentation up to 400 GHz

MMIC LNAs Design in ARIG



- 13.6 to 24 GHz LNA designed by Daniel White, William Mcgenn et. al
- WIN PP10-10 pHEMT technology
- Published in: [2019 IEEE Asia-Pacific Microwave Conference \(APMC\)](#)



- 75-110 GHz (ALMA Band 2 + 3) MMIC LNAs published by David Cuadrado-Calle, et. Al, 2017
- Three-stage MMICs using 35nm InP process at Northrop Grumman Corporation (NGC)



1. Challenges of MMIC LNA Design for PAF



ALMA



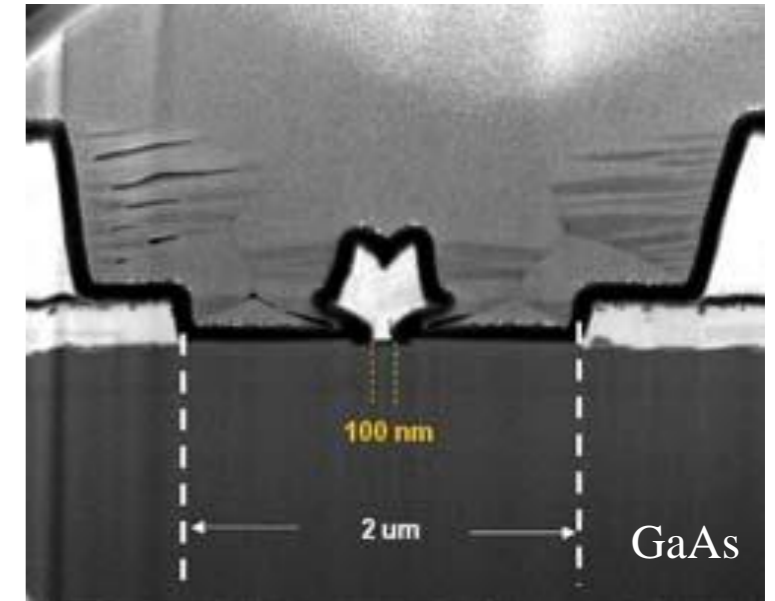
ASKAP

- A massive number of LNAs are required for Radio Telescope Arrays and Phase Array Feeds. These LNAs should have good consistent performance when there are used in a PAF.
- An accurate cryogenic model of transistors is needed for MMIC LNA design.
- Shortening the development cycle and reducing the price are also important considerations.

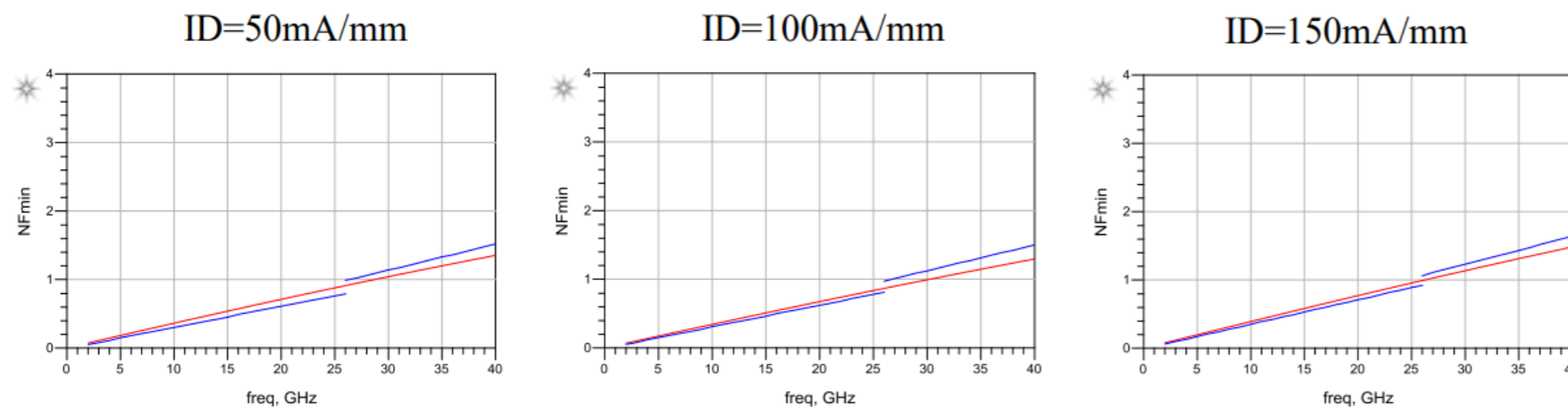
2. WIN and Diramics Commercial pHEMT Technology

1. WIN 0.1 μm GaAs pHEMT technology

- 100 nm gate length
- F_t greater than 135 GHz and F_{max} over 185 GHz
- The high degree of process maturity and commercially available technology
- Two 150mm GaAs fabs with monthly capacity of 24,000 wafers (2016)



www.microwavejournal.com



Device 15D04A075

$V_{ds} = 2.0 \text{ V}$

$I_{ds} = 50\text{mA/mm}, 100\text{mA/mm}$
and 150mA/mm

PP10-10 0.10 μm pHEMT Model Handbook_Ver1.3.3

2. Diramics PH-100 InP Technology

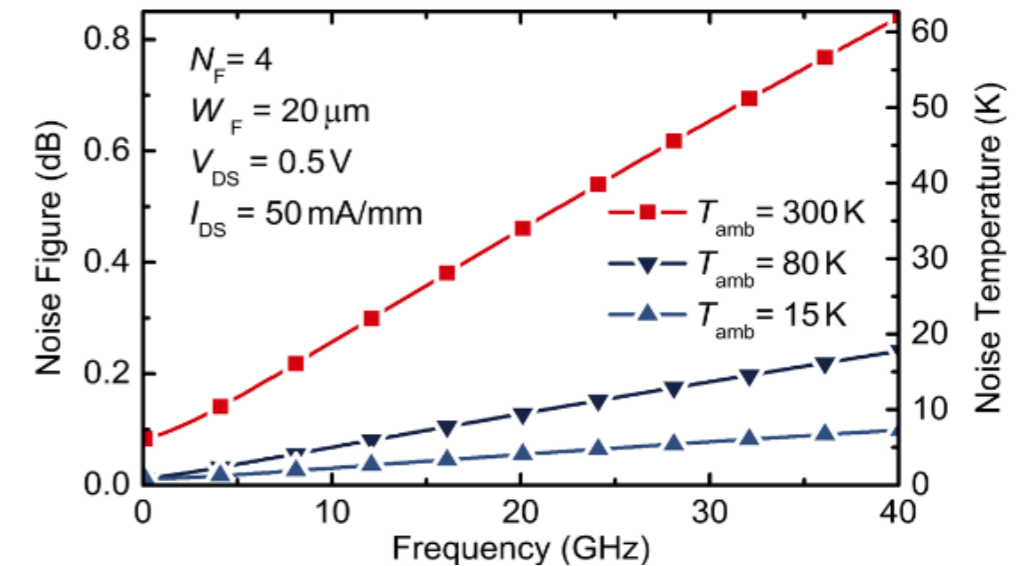


Available Dimensions for the pH-100 Technology

Gate Length:	100 nm
Finger Width:	10 μm – 150 μm
Number of Fingers:	2 / 4 / 6

Basic Characteristics of a 4 x 20 μm Device
(incl. bond-/probe- pads)

	300 K	15 K
f_T :	220 GHz	235 GHz
f_{MAX} :	550 GHz	800 GHz
gm:	1250 mS/mm	1500 mS/mm
NFmin (@30GHz)	0.6 dB	0.08 dB
Tmin (@30GHz)	43 K	5 K



www.diramics.com

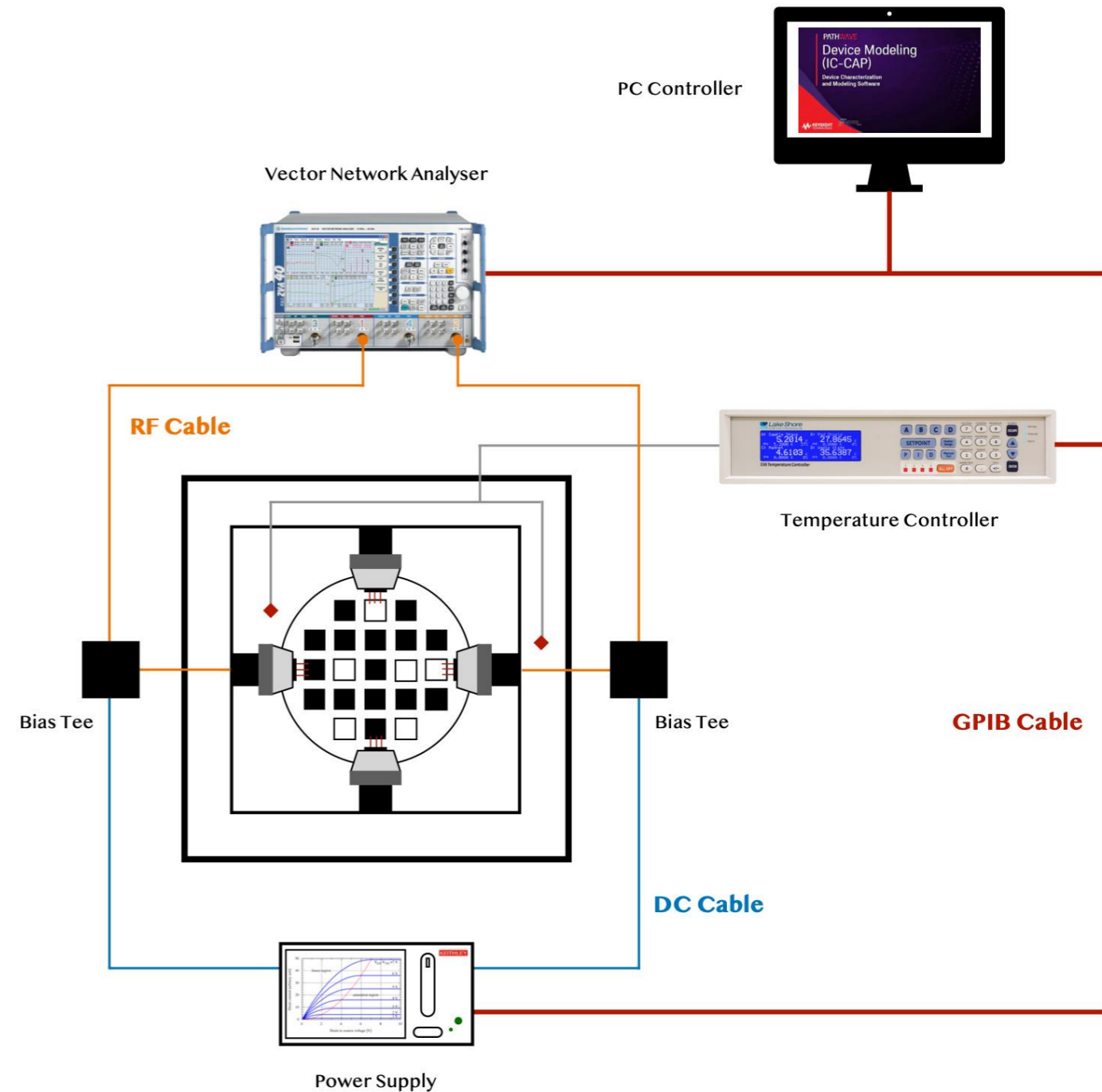
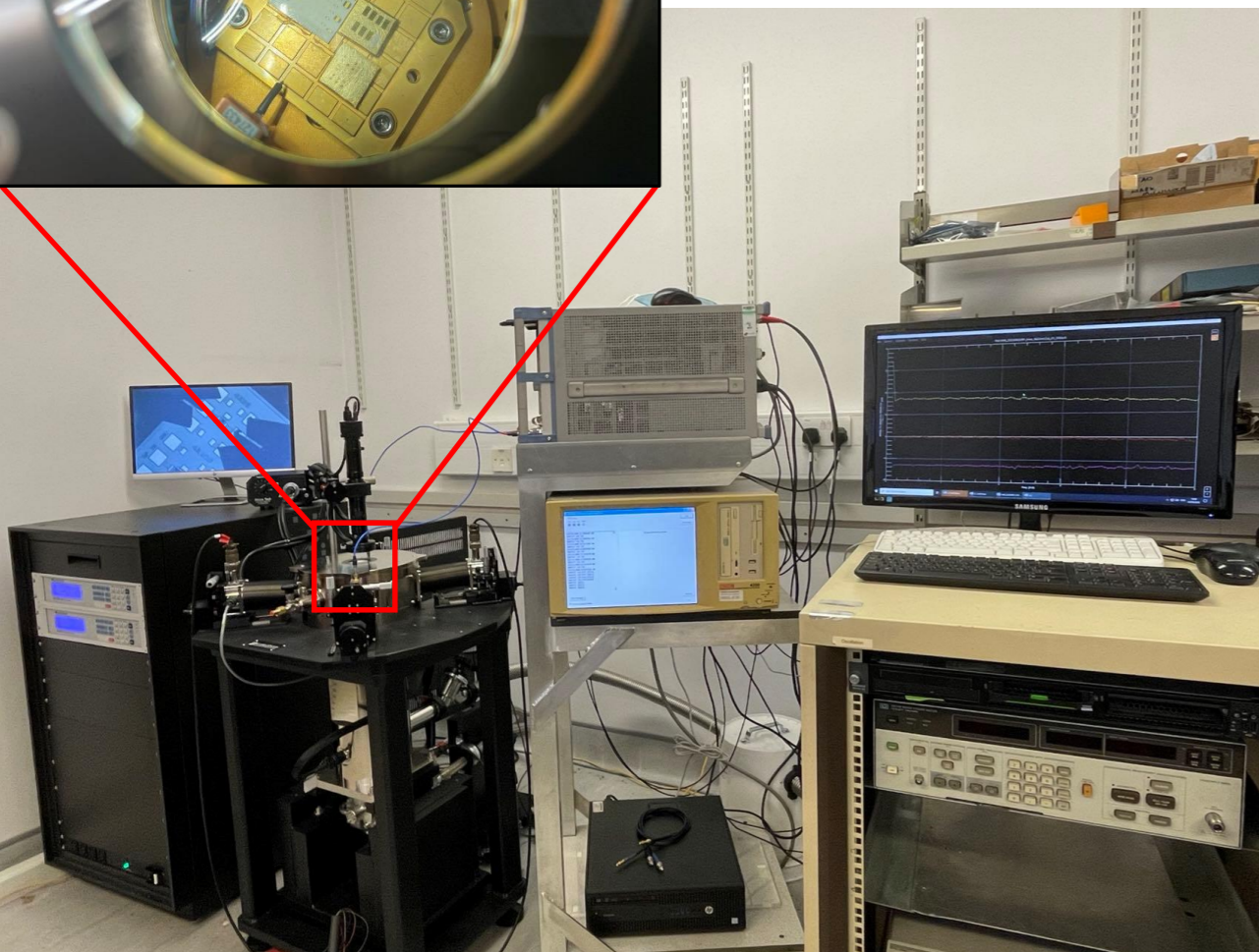
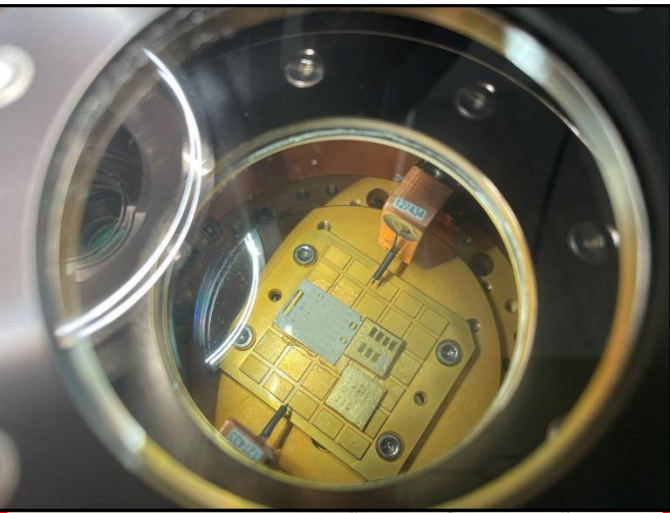
- 100 nm gate length InP-based pHEMT
- LNAs based on this technology are used in Yebes Astronomical Observatory and ESA ESTRACK
- MMIC process is possible



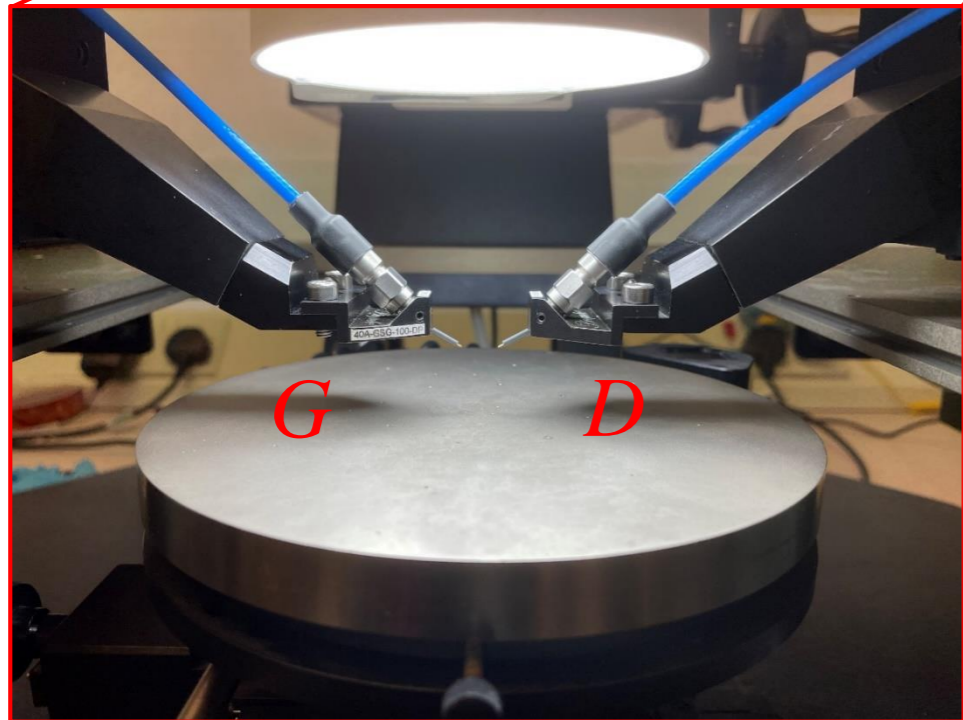
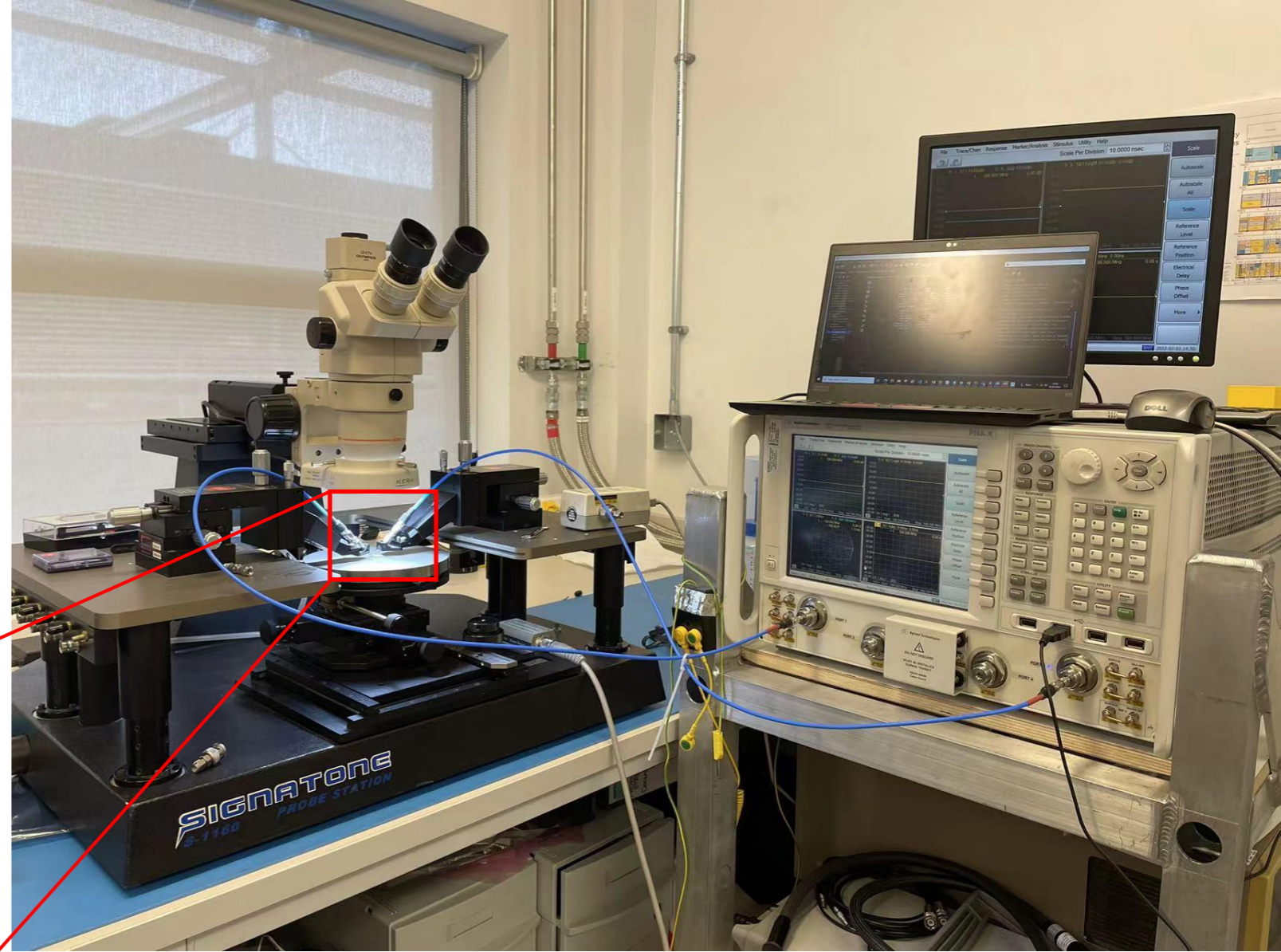
Low Noise Amplifier With 7-K Noise at 1.4 GHz and 25 °C. Sander Weinreb et. al 2021.

3. Transistors Characterizing and Modelling in ARIG

1. Probe Station Measurement System

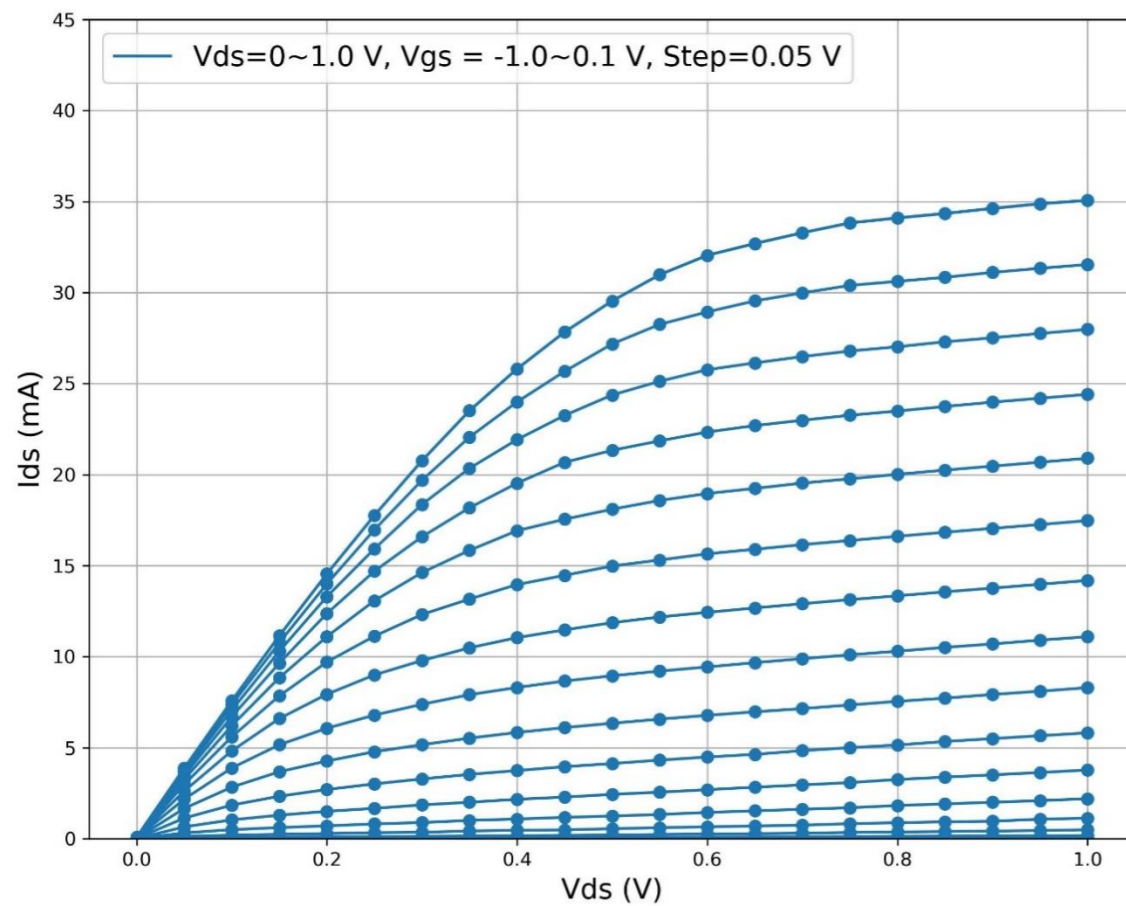
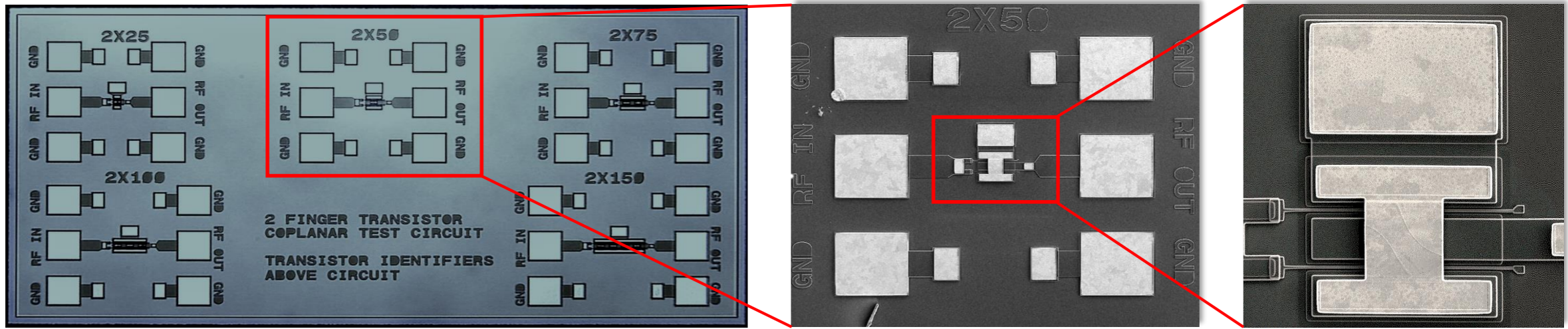


Lakeshore 4 K cryogenic probe station

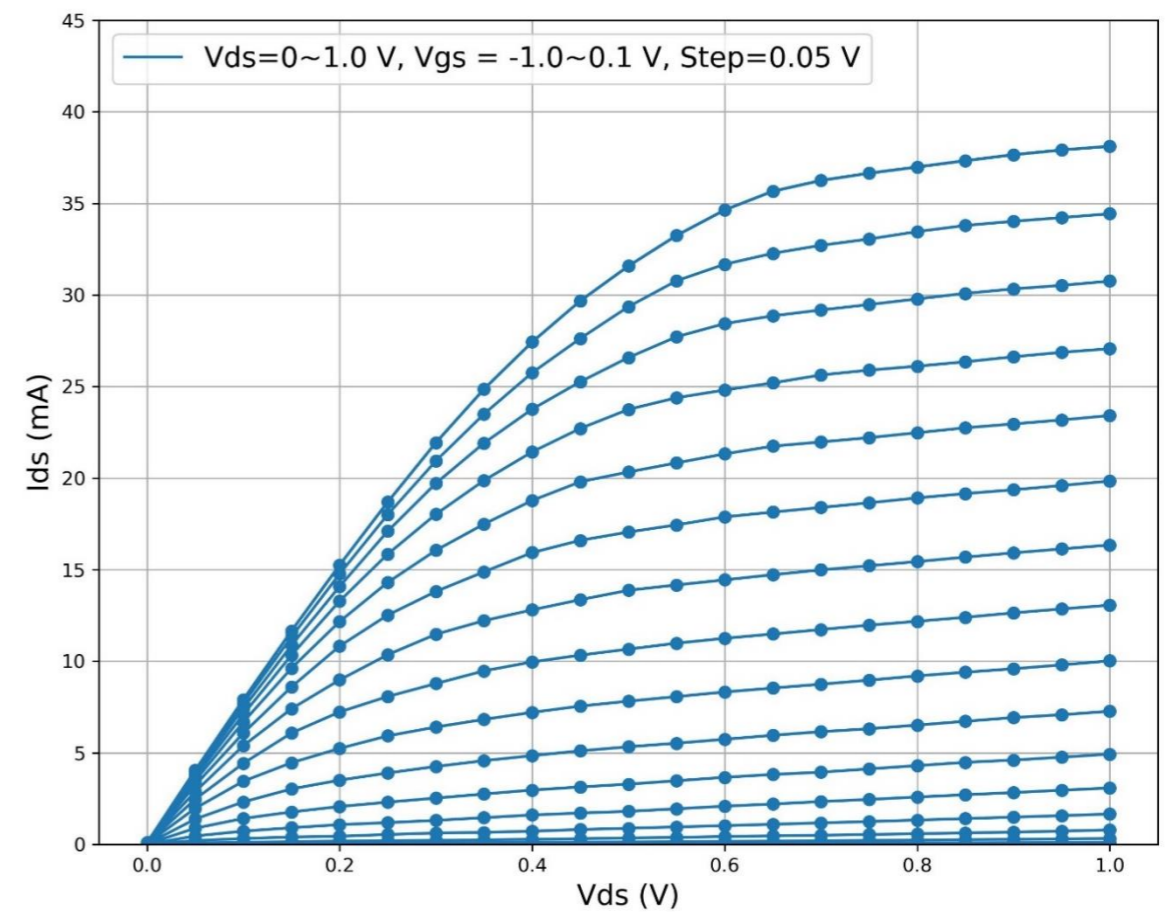


Signatone room temperature probe station

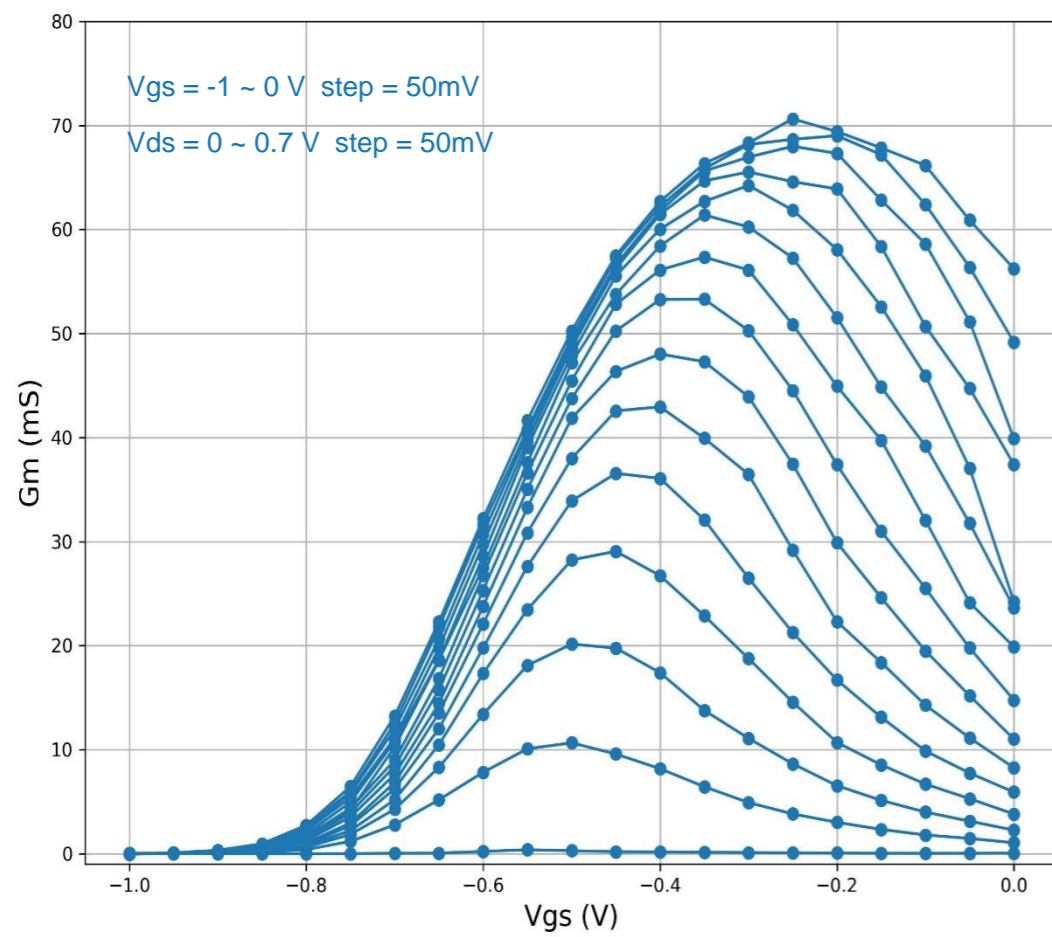
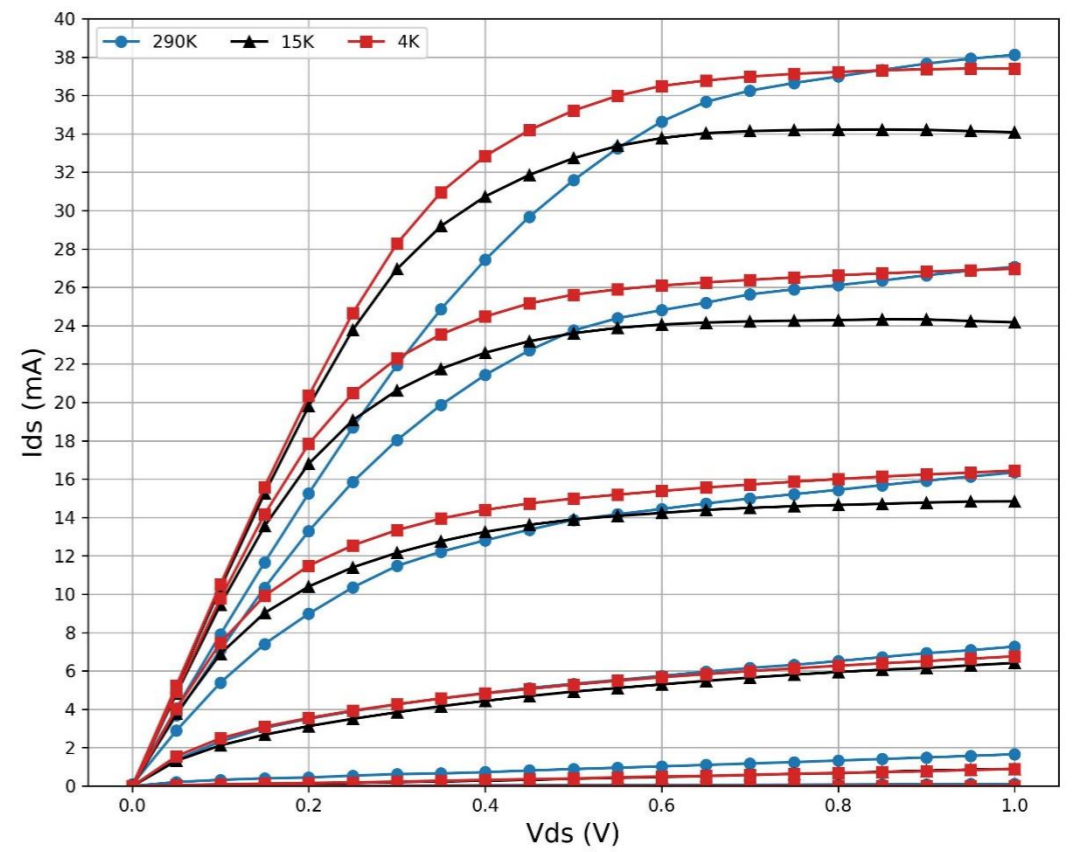
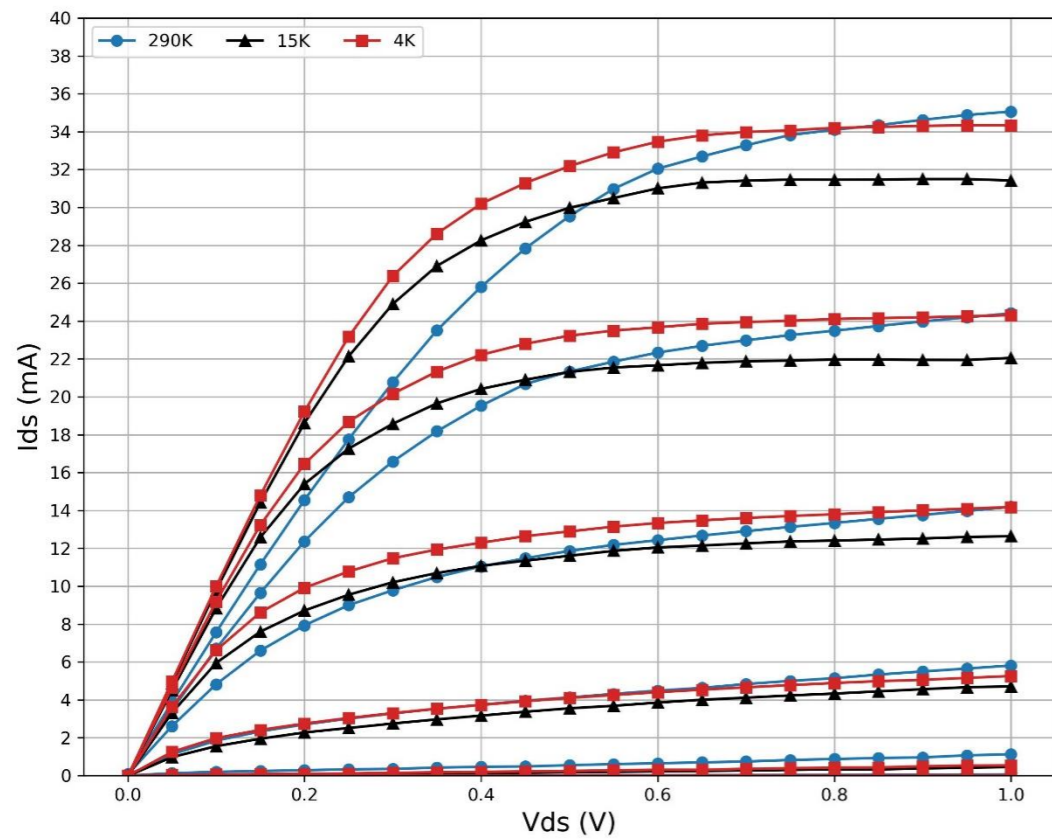
2. DC Measurement at 290K, 15K and 4K environment temperature



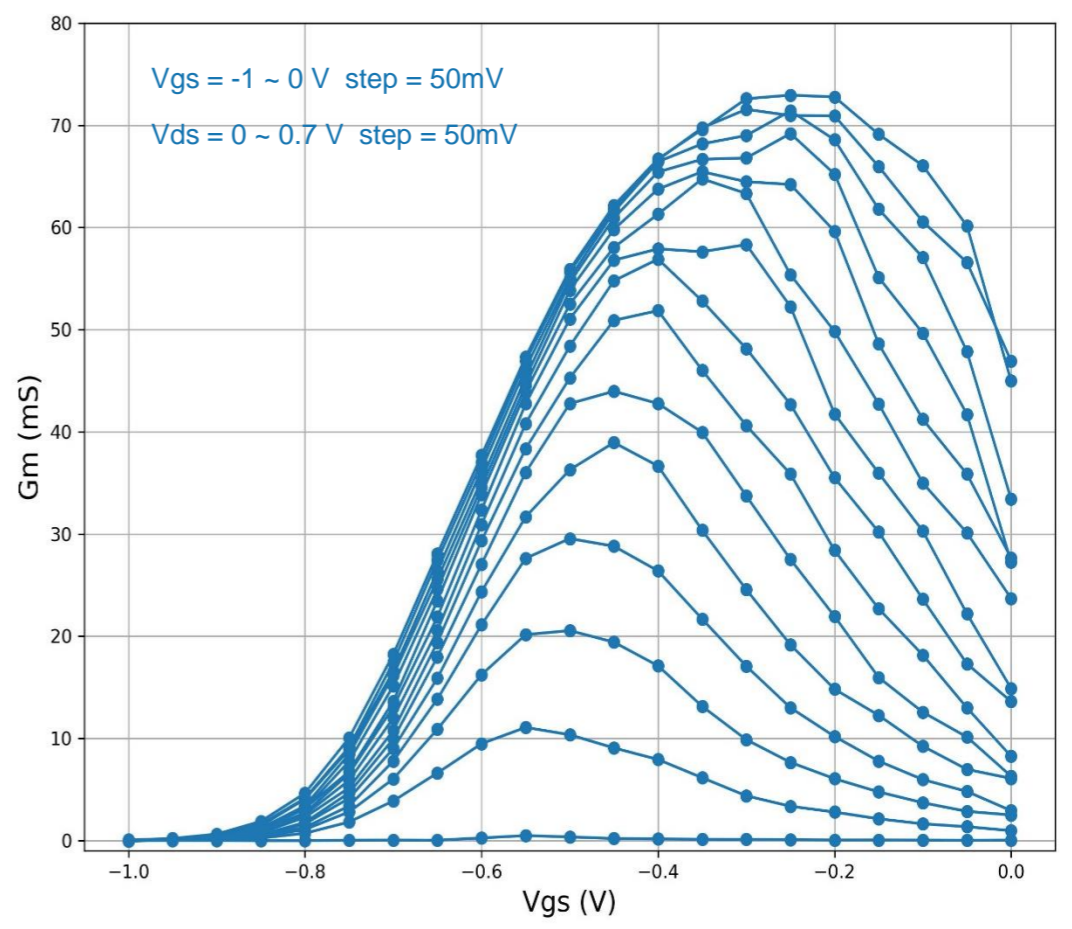
2F50um



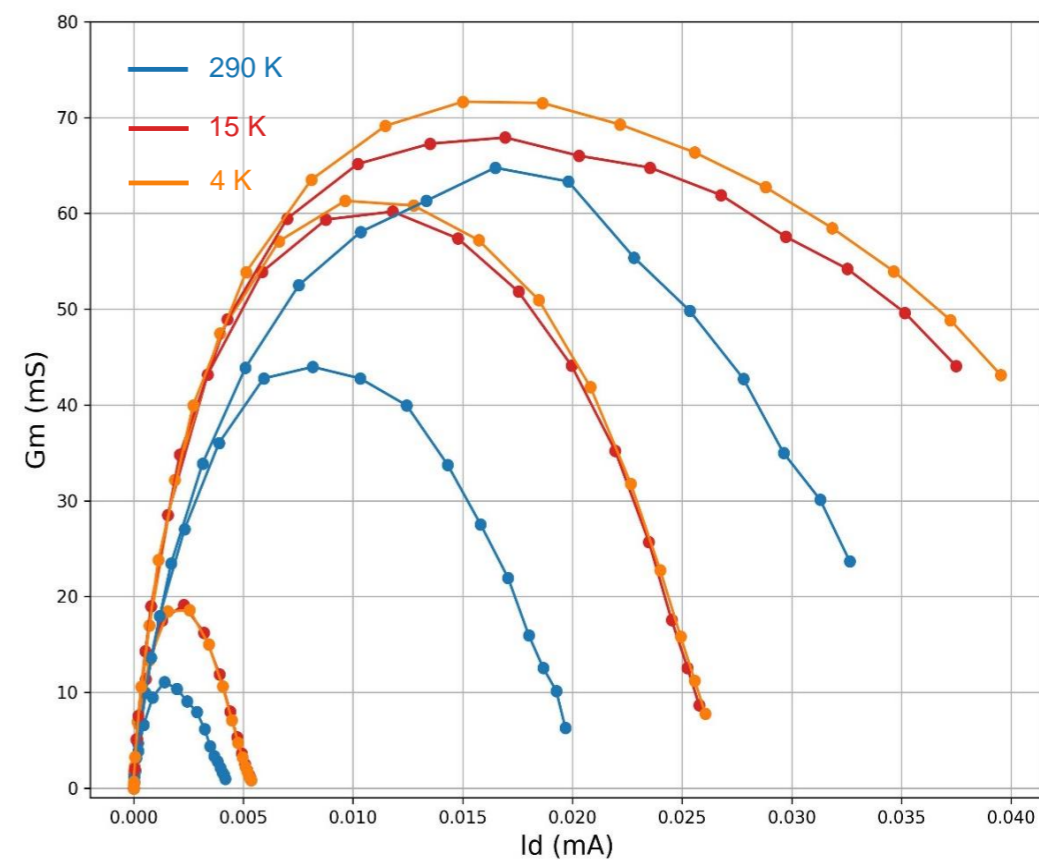
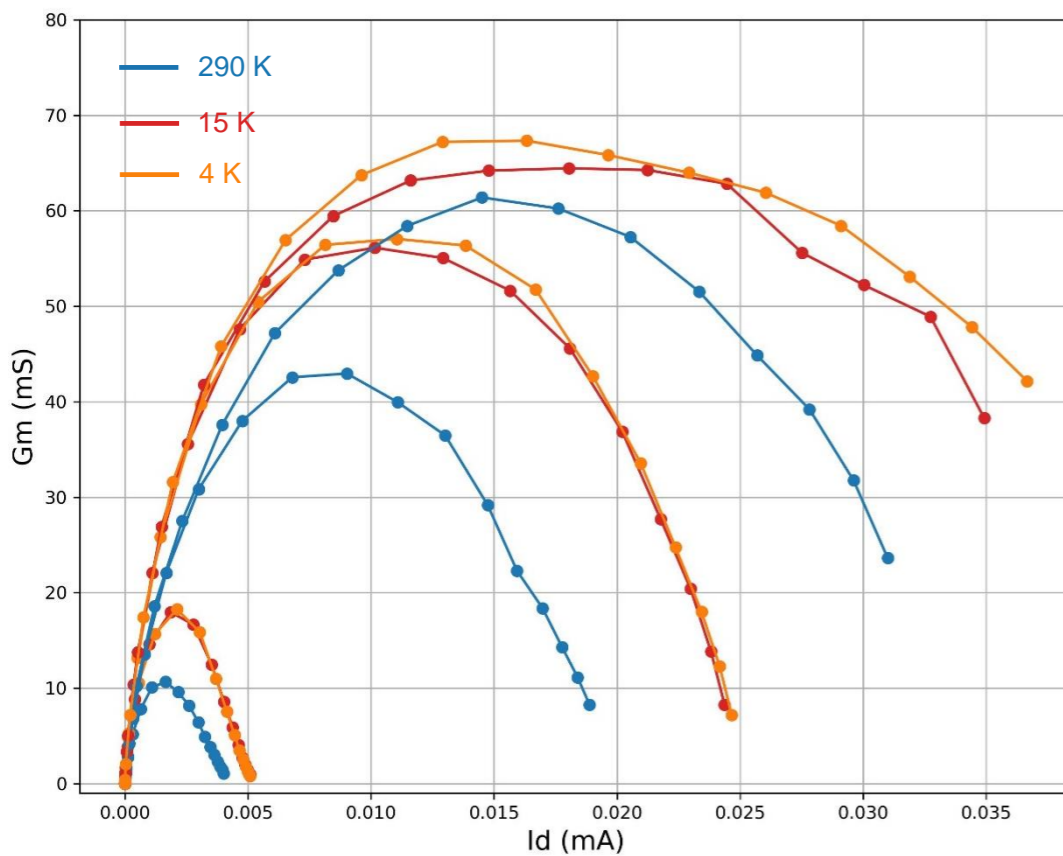
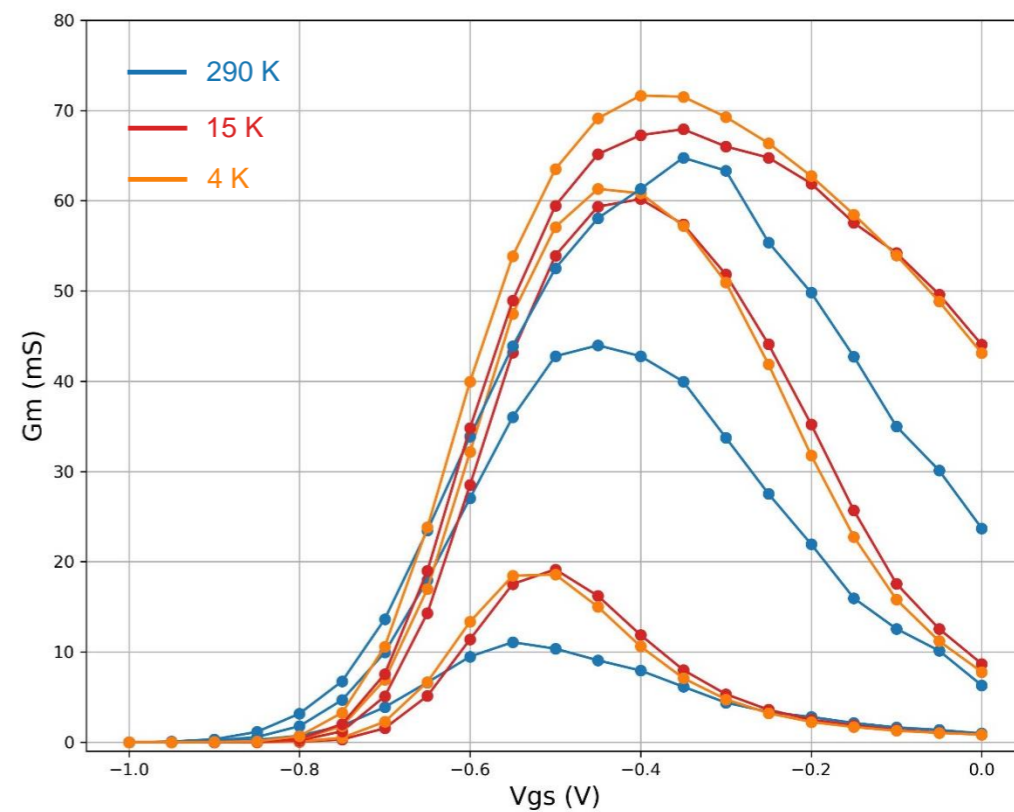
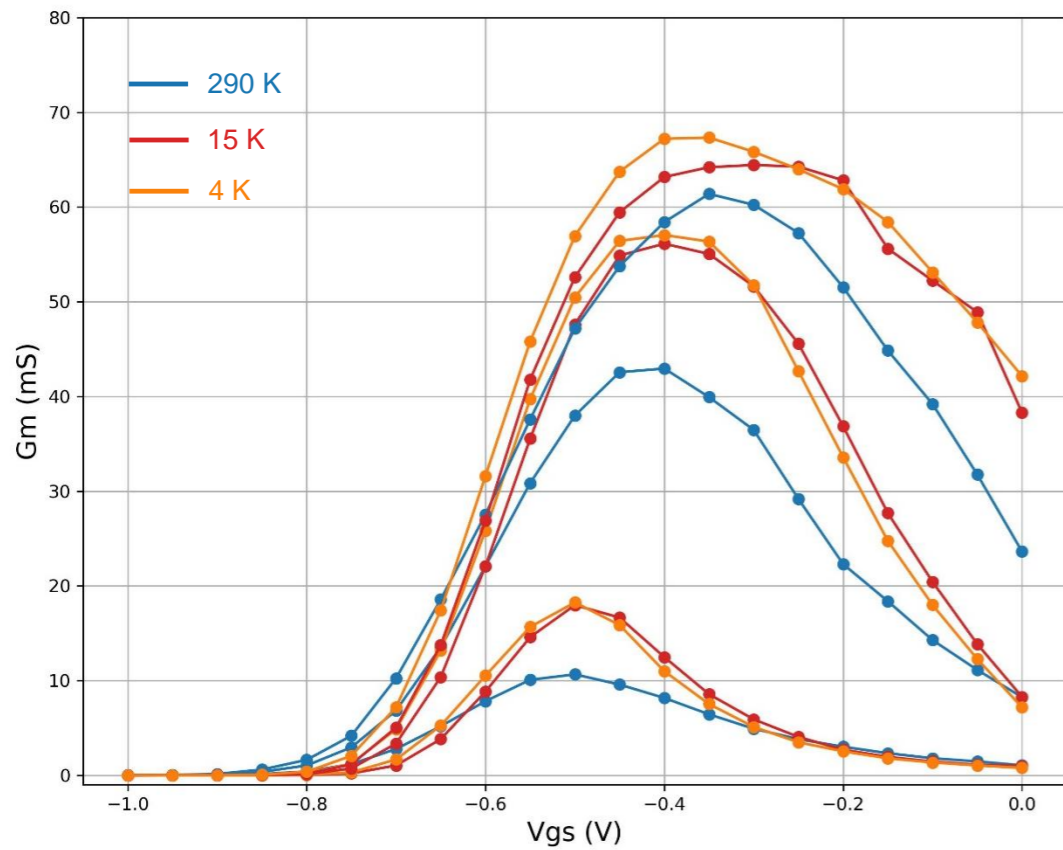
4F25um



2F50 μ m



4F25 μ m

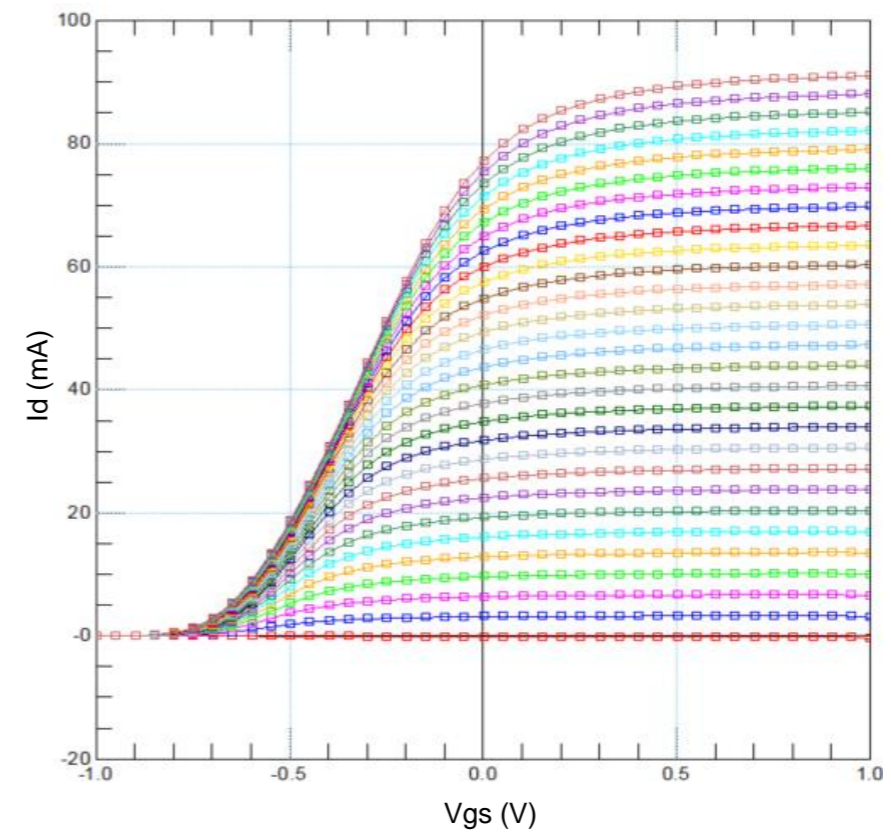
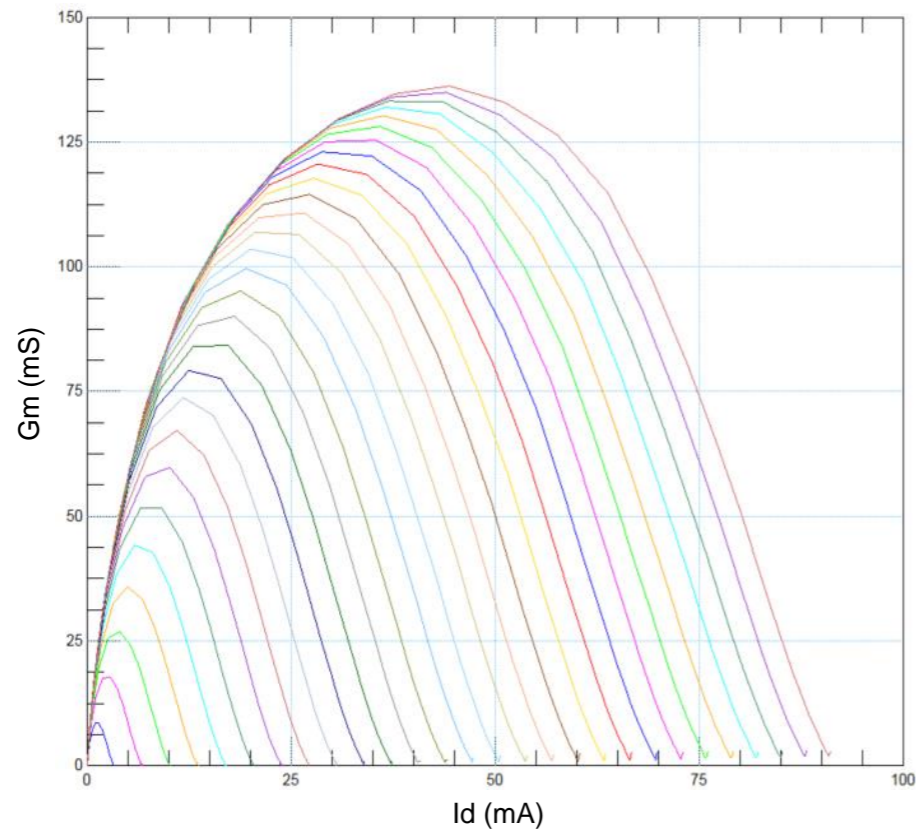
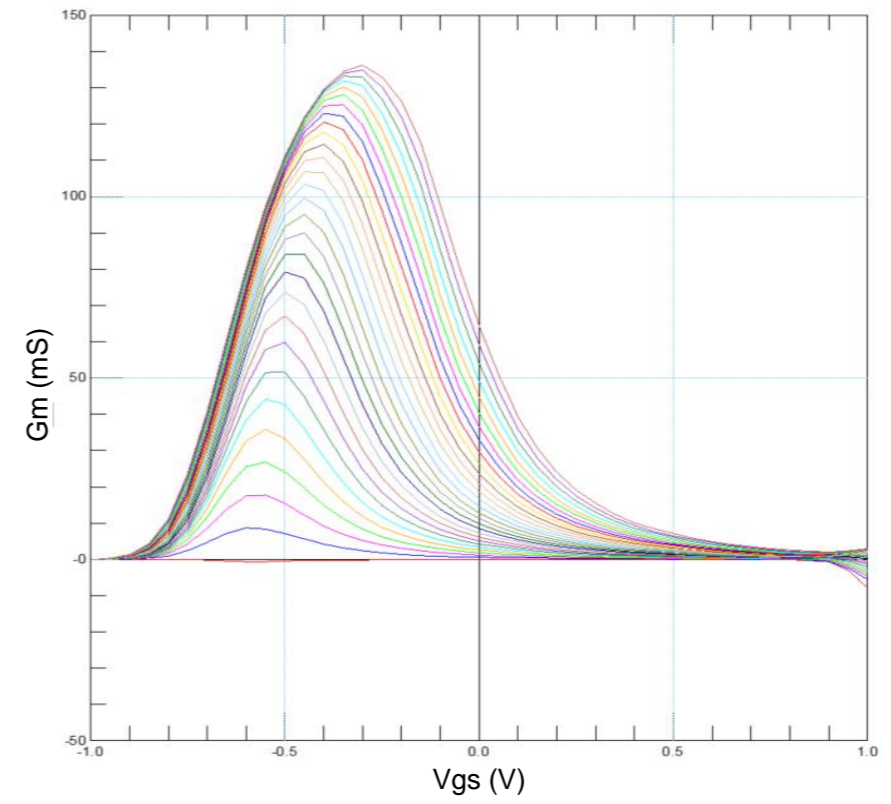
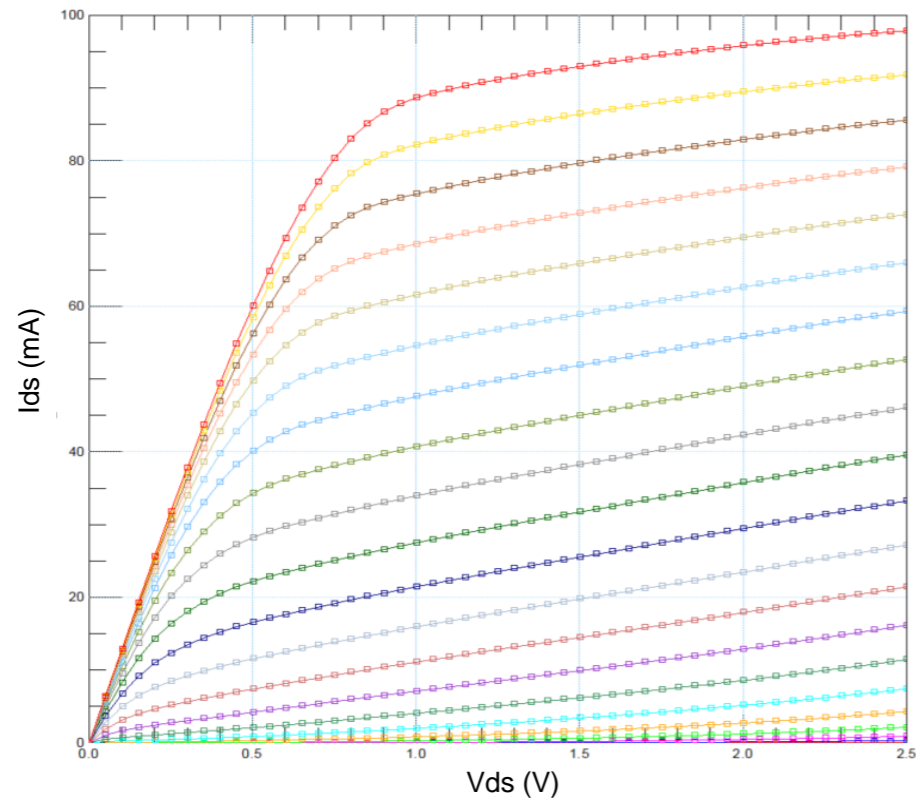


2F50 μ m

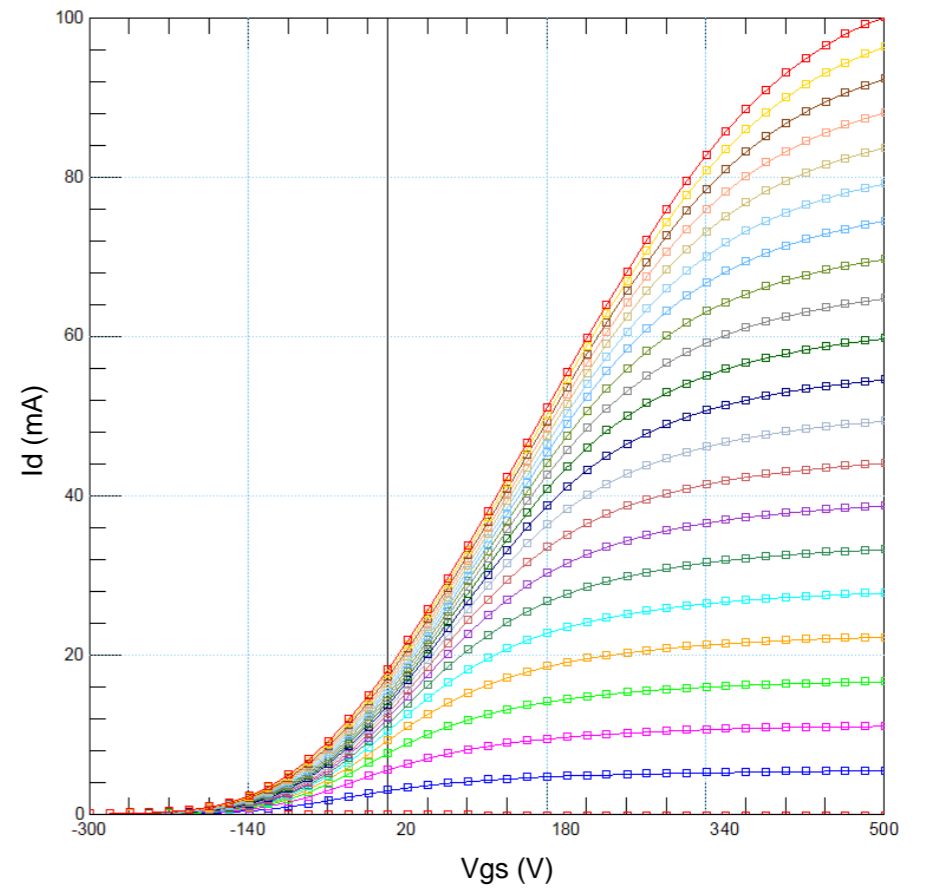
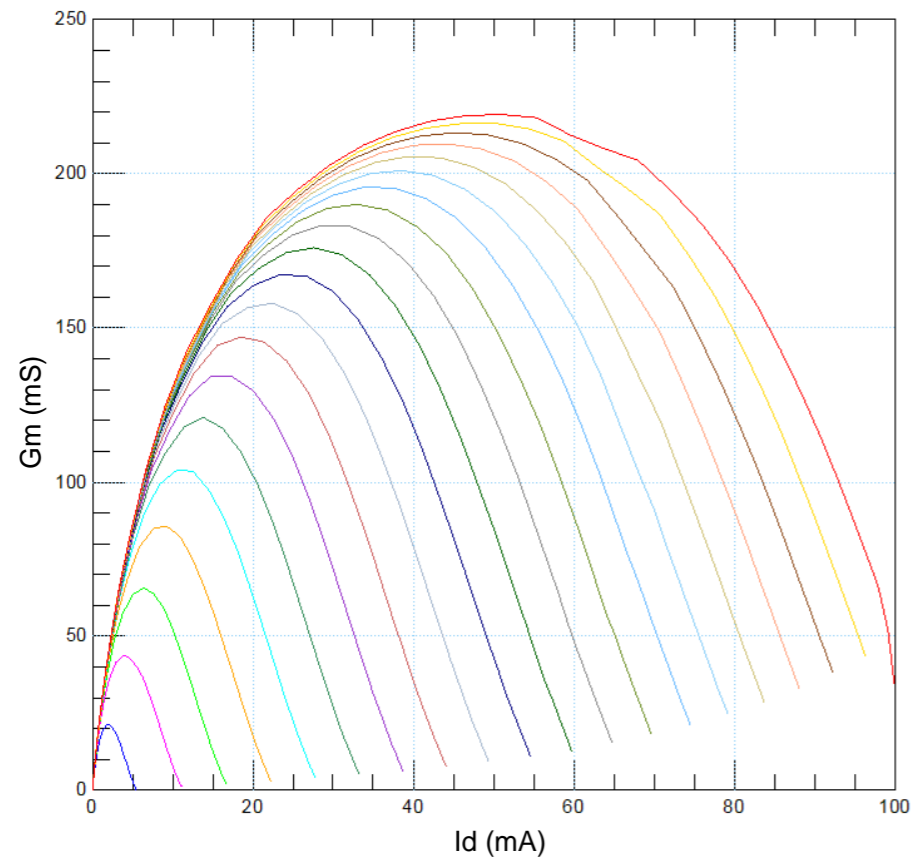
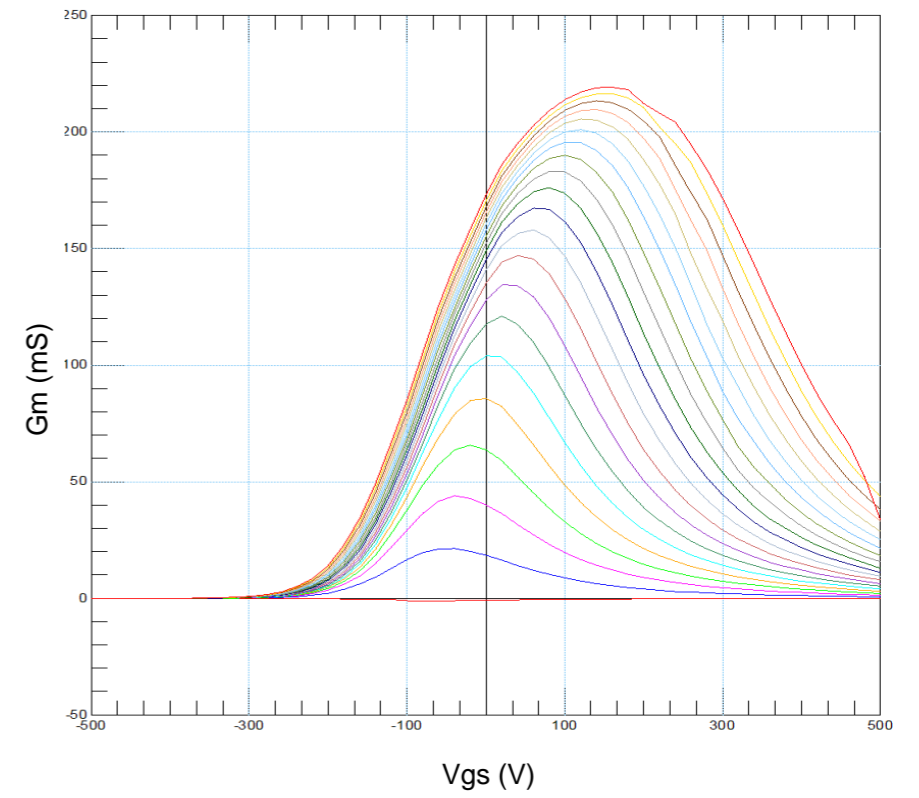
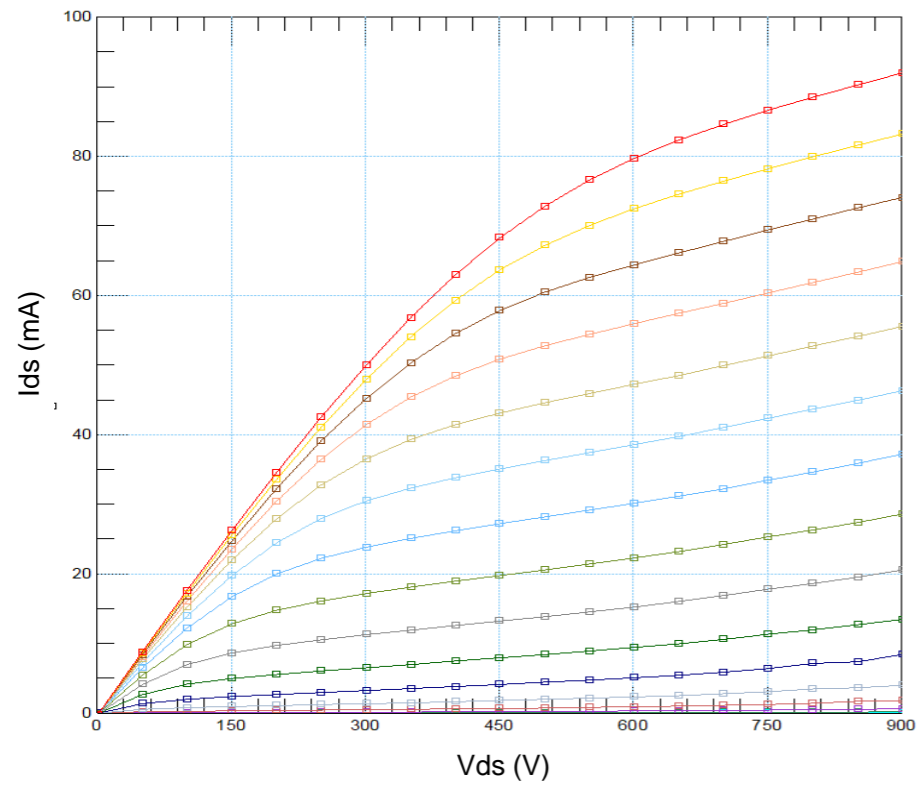
4F25 μ m

3. DC Measurement at 290 K and SSEC model extraction

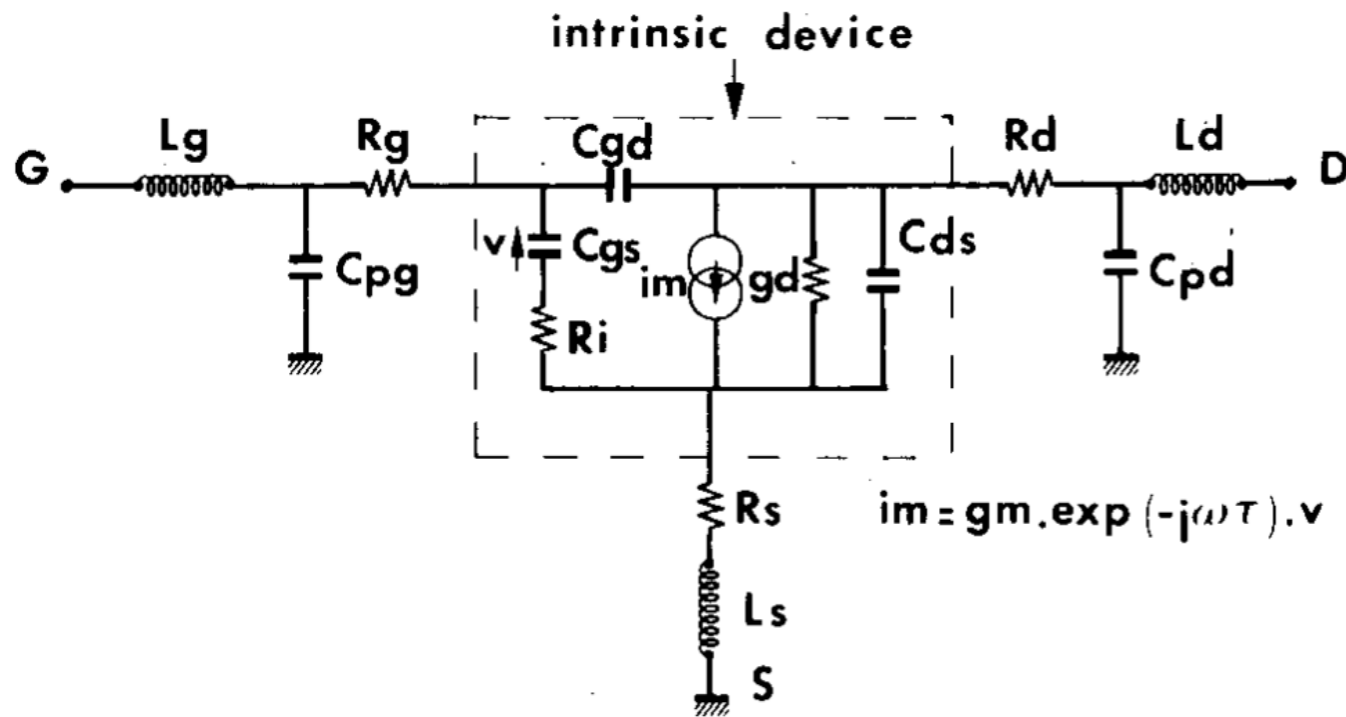
➤ *W4F50 um transistor*



➤ *D4F50 um transistor*

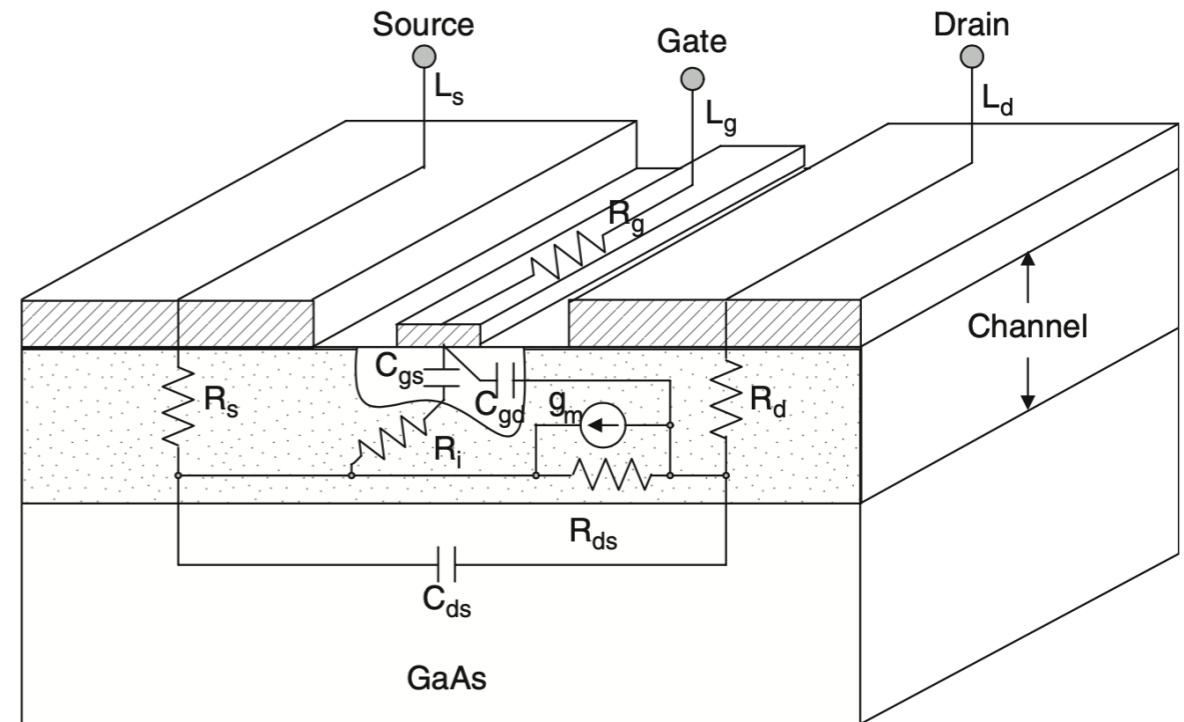


➤ *Small Signal Equivalent Circuit*



Small signal equivalent circuit of a field effect transistor.

Gilles Dambrine, 1998



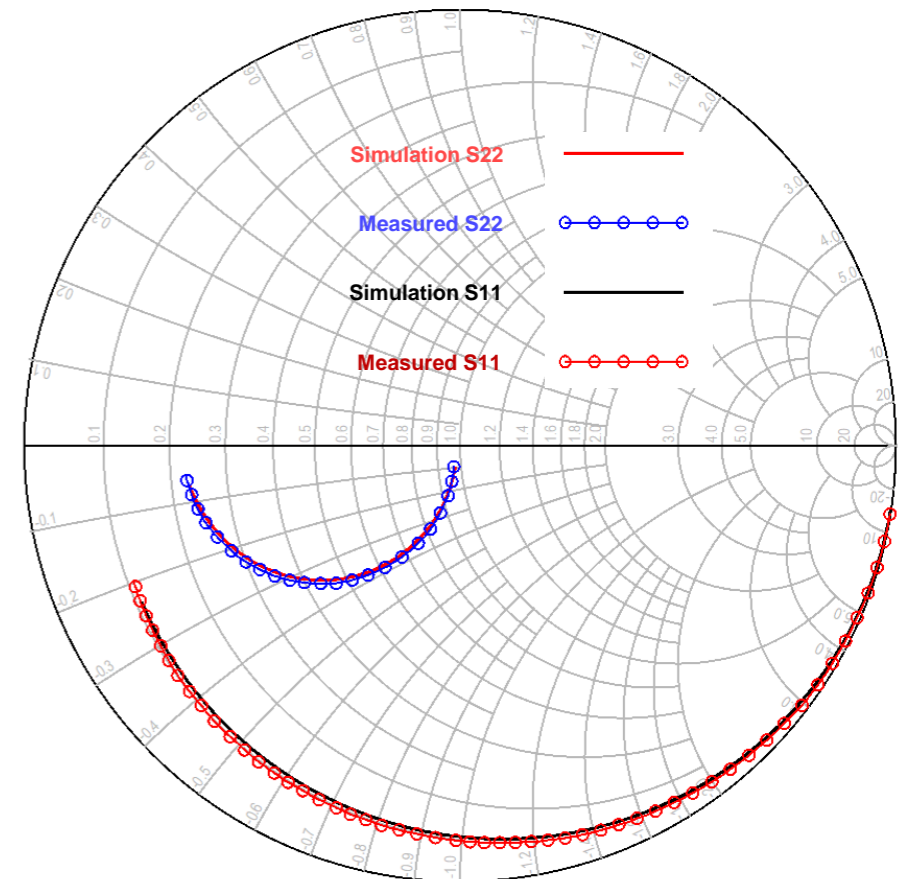
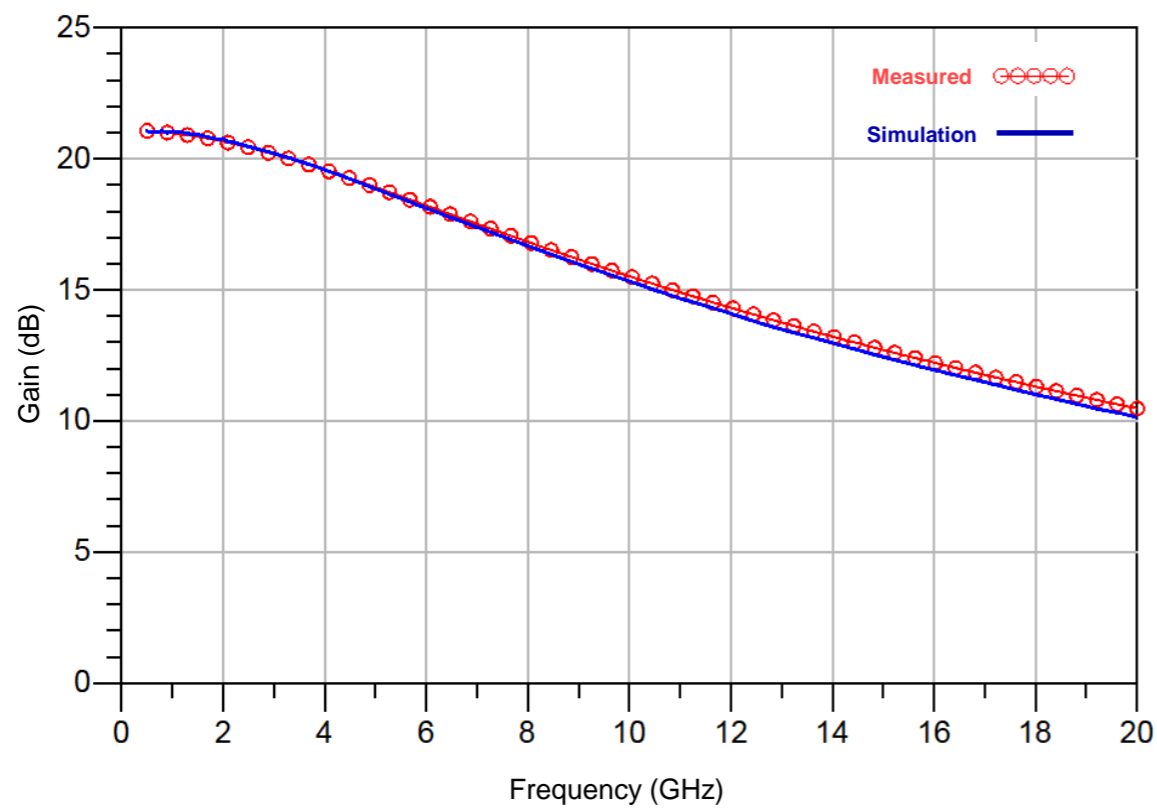
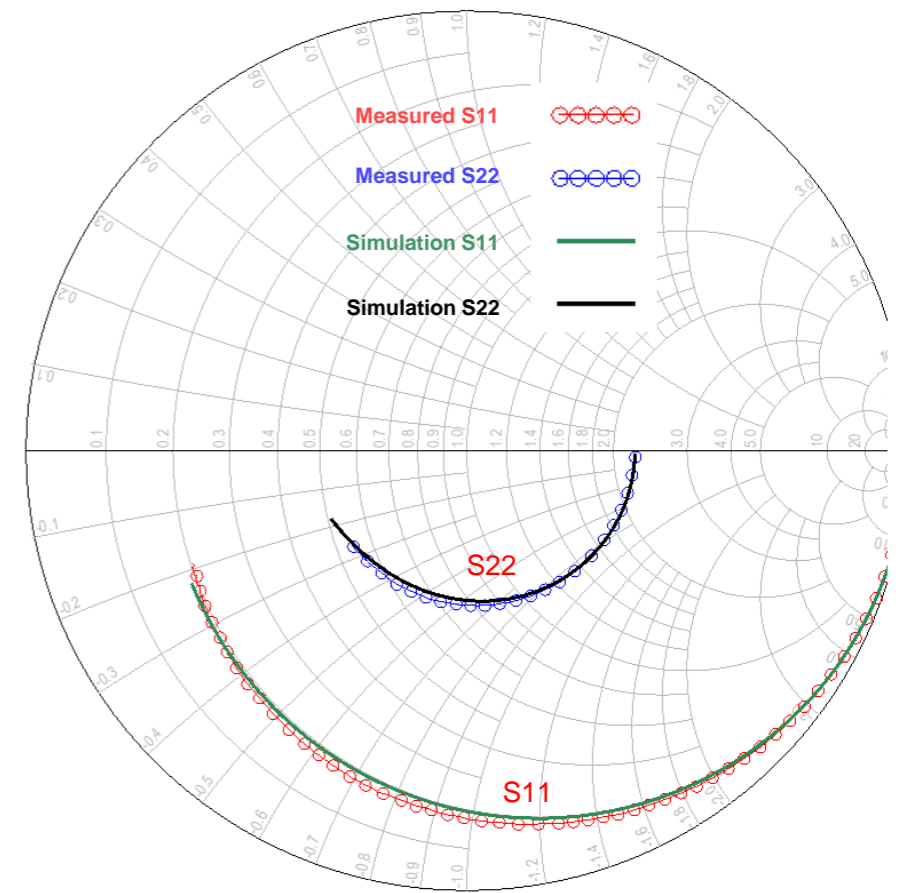
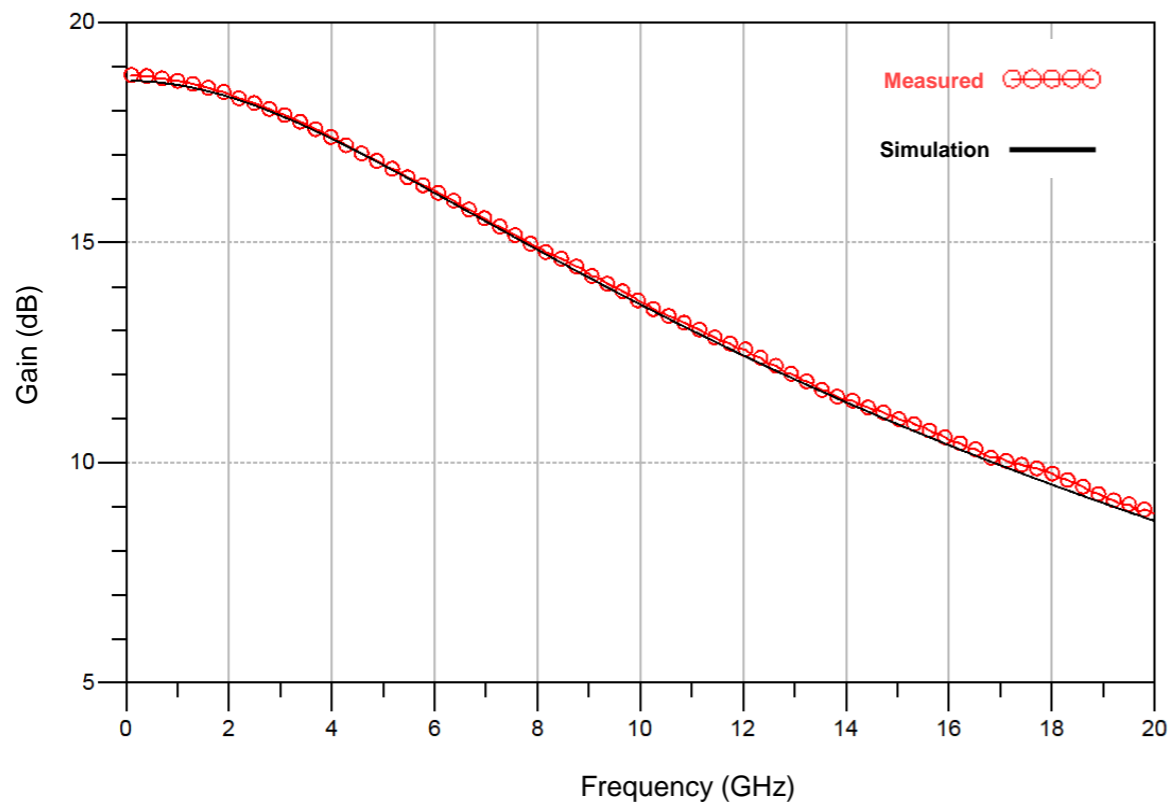
Small-signal equivalent circuit of a MESFET and the physical origin of the circuit element. Inder J. Bahl, 2009

- **Rg, Rs and Rd: three-terminal pad resistance**
- **Ld, Ls and L: three-terminal pad inductance**
- **Cpg and Cpd: gate and drain pad capacitance**

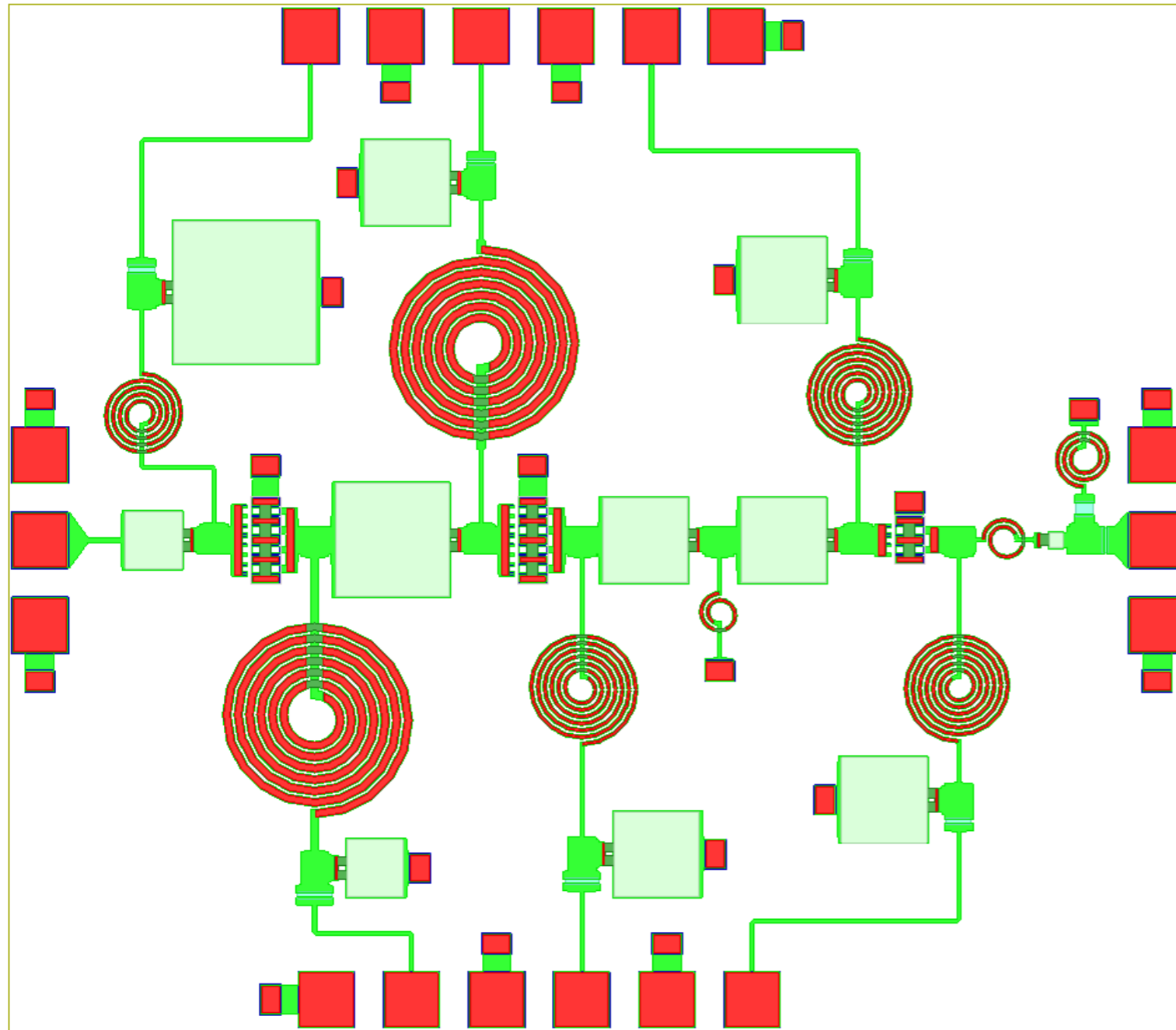
Extrinsic elements

- **Cgs: gate to source capacitance**
- **Cgd: feedback capacitance**
- **Ri: gate to source resistance**
- **Rds: drain to source resistance**

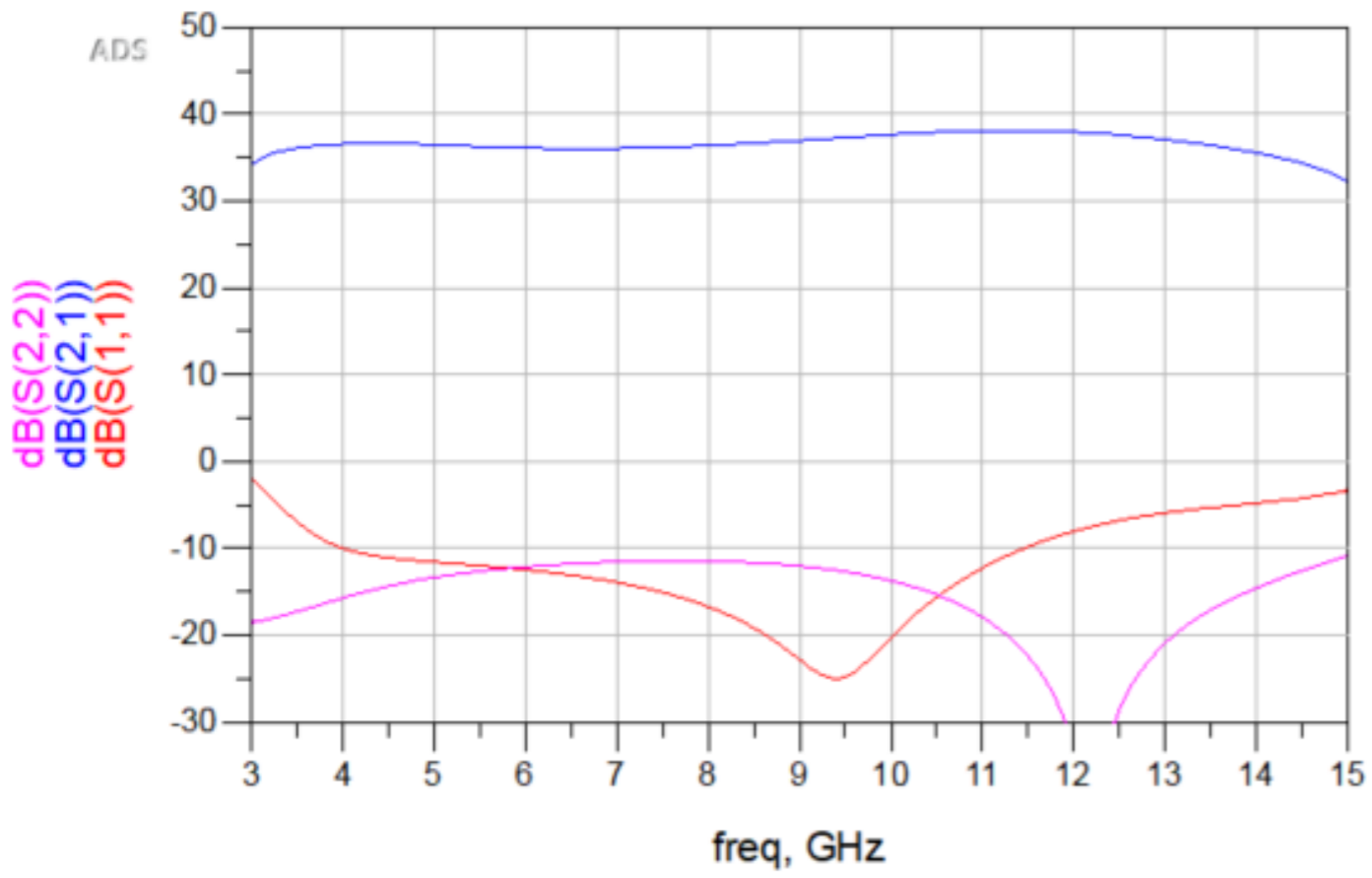
▪ **Tau: delay time** *Intrinsic elements*



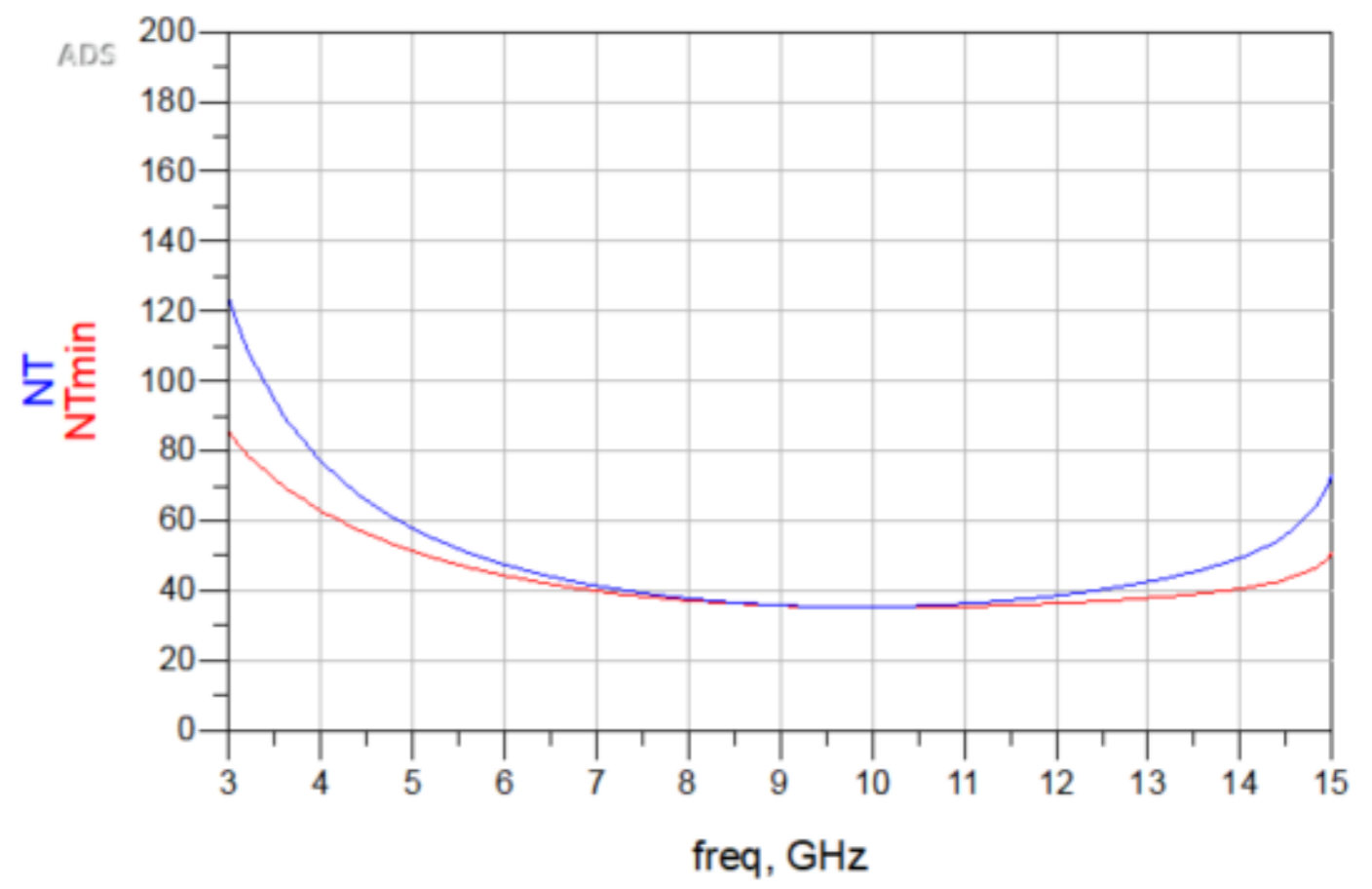
4. A 4 - 14 GHz MMIC LNA Design



- WIN PP10-10 Technology
- Three stages MMIC LNA with Two 8 x100 um and one 4x100 um transistors
- Size: 2.01mm * 1.80mm



- Gain: > 35 dB
- Noise temperature: 36 K (20 % bandwidth) and under 40 K (50 % bandwidth)



5. Future Work



1. Characterisation WIN and Diramics transistors while a gradient temperature changes from 4 K to 290 K. WIN's transistors include PP10-10 and PP10-20 technology.
2. Developing noise measurement system and extraction transistors' noise model from 4 K to 290 K environment.
3. WIN PP10-20 pHEMT transistors characterisation and modelling
4. LNAs design for radio telescope: MMIC LNAs designed using WIN technology and discrete LNAs designed using Diramics transistors.



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Thank you!
Any questions?



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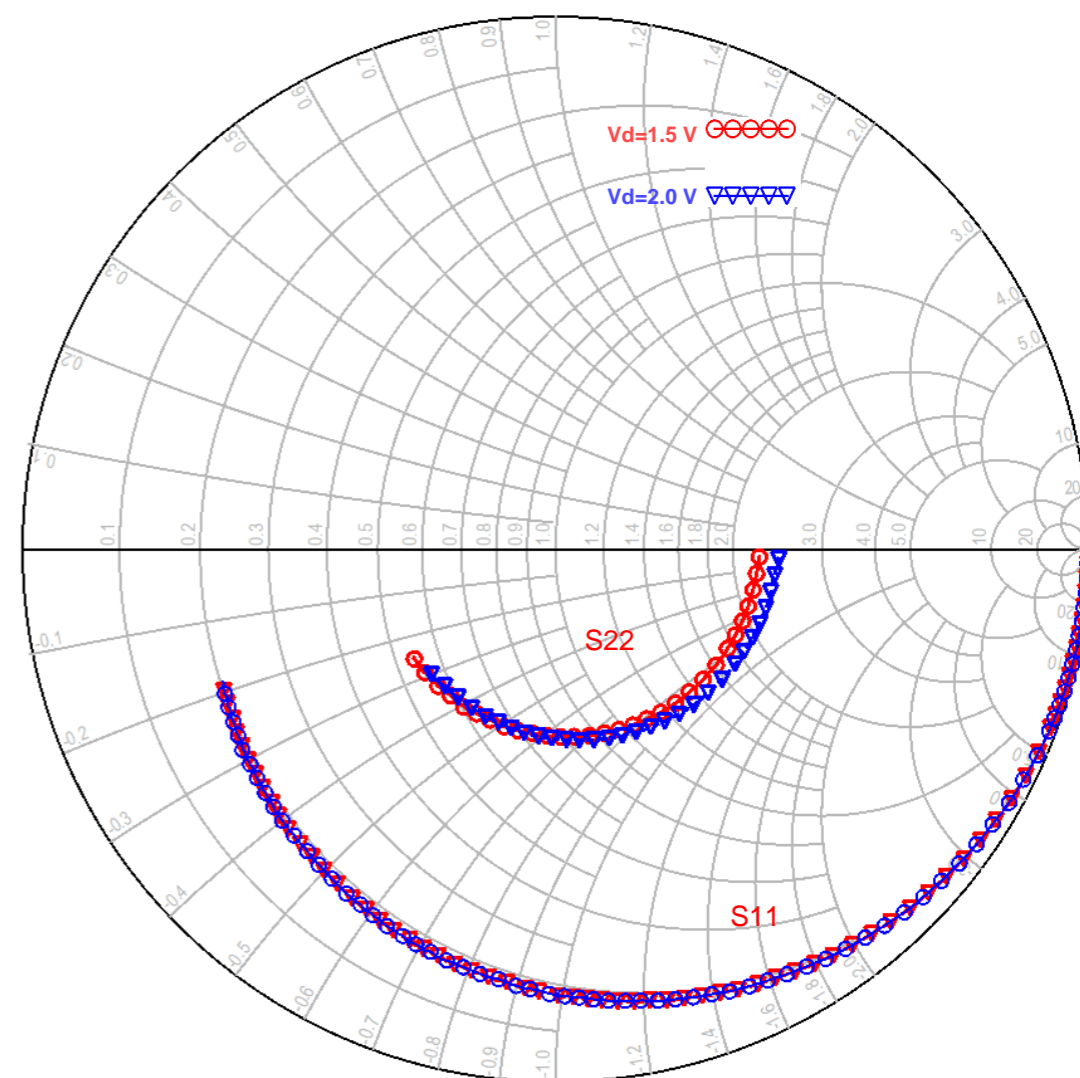
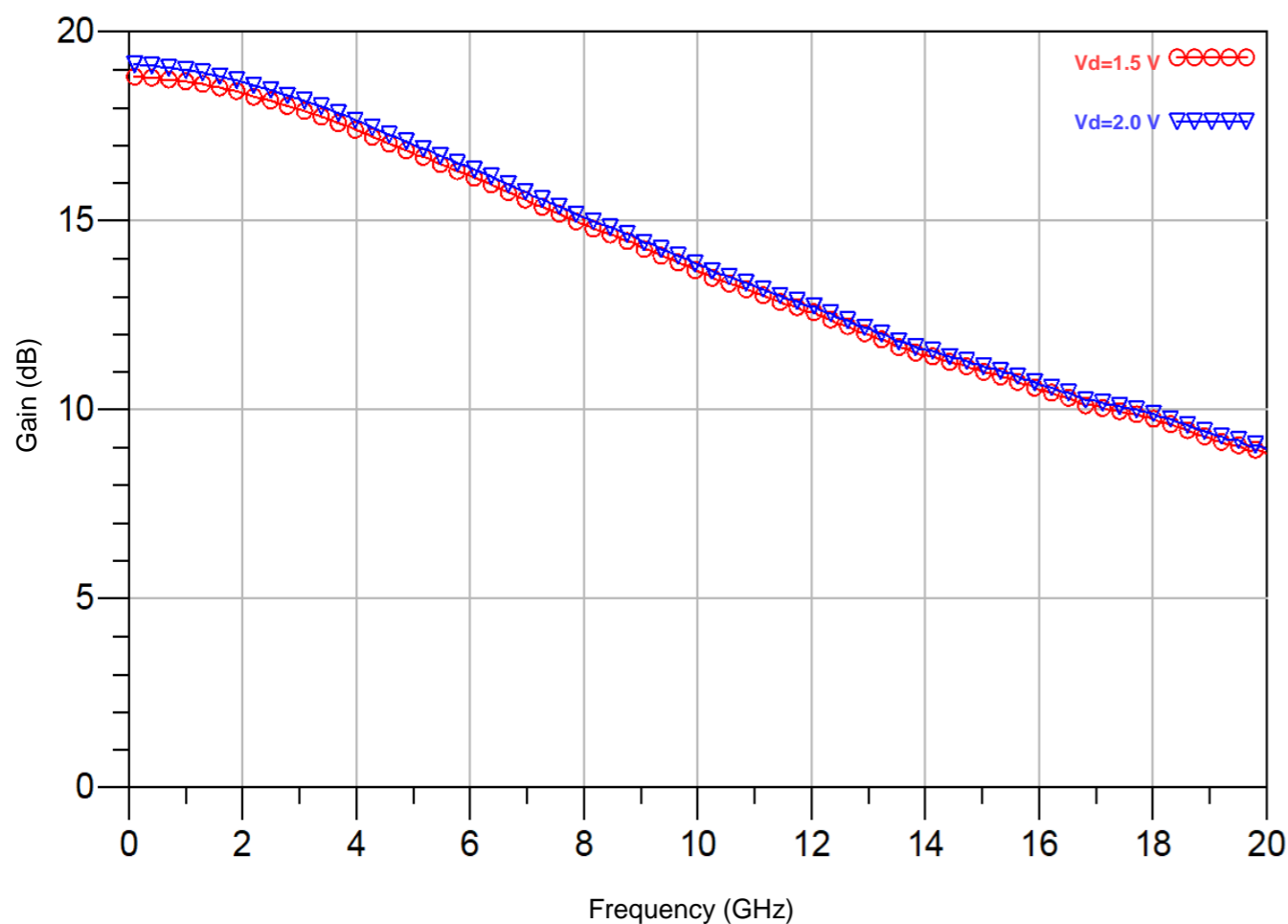


APPENDIX



➤ *S parameters measurement result*

- **Unbiased condition: $V_{ds} = V_{gs} = 0$ V**
- **Pinched condition: $V_{gs} = -1.0$ V, $V_{ds} = 0$ V**
- **Biased condition: $V_{gs} = -0.5$ V $V_{ds} = 1.5$ V and 2.0 V**
- **Frequency range: $0.1 \sim 20$ GHz**



➤ *S parameters measurement result*

- **Unbiased condition: $V_{ds} = V_{gs} = 0$ V**
- **Pinched condition: $V_{gs} = -0.4$ V, $V_{ds} = 0$ V**
- **Biased condition: $V_{ds} = 0.6$ V, $V_{gs} = 0, 0.05, 0.1, 0.15$ and 0.20 V**
- **Frequency range: 0.1 ~ 20 GHz**

